



**THE 38TH IEEE INTERNATIONAL CONFERENCE
ON MICRO ELECTRO MECHANICAL SYSTEMS**

FINAL PROGRAM

General Co-Chairs:
Hyunjoo “Jenny” Lee
KAIST, Korea

Sheng-Shian Li
NTHU, Taiwan

Sponsored by



CONFERENCE AT A GLANCE

SUNDAY, 19 JANUARY

12:00-19:00	Conference Registration and Check-In
13:00-17:10	Industry Session (Room 304a)
17:10-19:00	Welcome Reception (Room 305)

MONDAY, 20 JANUARY

08:00-08:25	Welcome Address (Room 301)	
08:25-08:45	• IEEE Fellows Recognition in the Field of MEMS/NEMS • IEEE EDS Robert Bosch Micro and Nano Electro Mechanical Systems Award	
08:45-09:30	Plenary Presentation I (Room 301) Tien Wu – <i>Advanced Semiconductor Engineering, Inc (ASE), TAIWAN</i>	
09:30-10:30	Session I - Medical MEMS (Room 301)	
10:30-11:00	Break and Exhibit Inspection (Hall S2)	
11:00-12:00	Session II - Electromagnetic MEMS (Room 301)	
12:00-12:05	MEMS Community Announcement (Room 301)	
12:05-13:05	Lunch and Exhibit Inspection (Hall S2)	
12:05-13:05	Student Mixer (Central Boulevard – West Lobby Side)	
13:05-14:05	Session IIIa - Inertial MEMS (Room 304a)	Session IIIb - Biomedical Sensing (Room 304b)
14:05-14:10	Transition	
14:10-15:10	Session IVa - 3D MEMS (Room 304a)	Session IVb - In Vitro Assays (Room 304b)
15:10-17:00	Poster Session I (Hall S2)	
15:10-15:40	Break and Exhibit Inspection (Hall S2)	
17:00	Adjourn for the Day	

TUESDAY, 21 JANUARY

08:15-09:00	Plenary Presentation II (Room 301) Kurt Petersen – <i>Silicon Valley Band of Angels, USA</i>	
09:00-10:00	Session V - Acoustic MEMS (Room 301)	
10:00-10:30	Break and Exhibit Inspection (Hall S2)	
10:30-11:45	Session VI - 3D Manufacturing (Room 301)	
11:45-12:00	MEMS 2026 Announcement (Room 301)	
12:00-13:00	Lunch and Exhibit Inspection (Hall S2)	
13:00-15:00	Poster Session II (Hall S2)	
14:20-14:50	Break and Exhibit Inspection (Hall S2)	

CONFERENCE AT A GLANCE

TUESDAY (continued)

14:20-14:50	Student Led Conference Session I (Hall S2)	
15:00-16:00	Session VIIa - MEMS for Computing (Room 304a)	Session VIIb - Soft MEMS (Room 304b)
16:00-16:05	Transition	
16:05-16:50	Session VIIa - Metrology Using MEMS (Room 304a)	Session VIIb - Physical Sensing (Room 304b)
16:50	Adjourn for the day	
18:30-21:00	Conference Banquet (Marriott Hotel)	

WEDNESDAY, 22 JANUARY

08:15-09:00	Plenary Presentation III (Room 301) Han Chung – <i>i3system, KOREA</i>	
09:00-10:00	Session IX - Resonators (Room 301)	
10:00-10:30	Break and Exhibit Inspection (Hall S2)	
10:30-11:45	Session X - Mechanical Cell Manipulation (Room 301)	
11:45-13:00	Lunch and Exhibit Inspection (Hall S2)	
11:45-13:00	Women in Engineering Networking Luncheon (Central Boulevard – West Lobby Side)	
13:00-14:00	Session XIa - Neural Interface I (Room 304a)	Session XIb - Biomedical Ultrasound (Room 304b)
14:00-14:10	Transition	
14:10-15:10	Session XIIa - Neural Interface II (Room 304a)	Session XIIb - Nano Material (Room 304b)
15:10-17:10	Poster Session III (Hall S2)	
16:40-17:10	Break and Exhibit Inspection (Hall S2)	
16:40-17:10	Student Led Conference Session II (Hall S2)	
17:10	Adjourn for the day	
18:00-20:30	Reunion and Networking Night (Sunset Beach)	

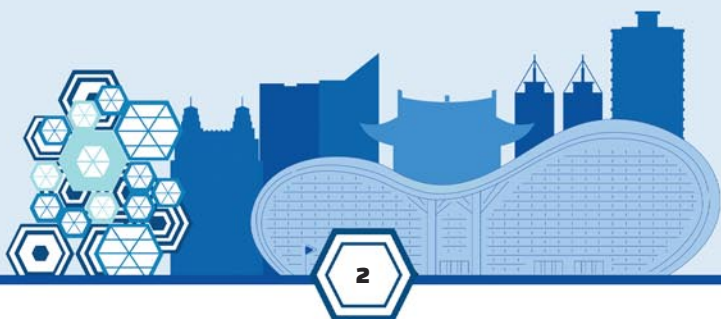
THURSDAY, 23 JANUARY

08:15-09:00	Plenary Presentation IV (Room 304a) Sabeth Verpoorte – <i>University of Groningen, NETHERLANDS</i>	
09:00-10:00	Session XIII - Innovative Sensor (Room 304a)	
10:00-10:30	Break and Exhibit Inspection (Hall S2)	
10:30-11:30	Session XIV - Environmental Sensing (Room 304a)	
11:30-12:00	Awards Ceremony and Final Remarks (Room 304a)	
12:00	Conference Adjourns	
13:00-16:50	ASE Kaohsiung Technical Tour	

Plenary Speakers **3**
 Invited Speakers **4**
 Invited Student Speakers **5**
 Robert Bosch Award Recipient **6**

TECHNICAL PROGRAM

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MONDAY, 20 JANUARY — 08:45 (Room 301)



Plenary Presentation I

Tien Wu – *Advanced Semiconductor Engineering, Inc (ASE), TAIWAN*

NAVIGATING THE NEW NORMAL

TUESDAY, 21 JANUARY — 08:15 (Room 301)



Plenary Presentation II

Kurt Petersen – *Silicon Valley Band of Angels, USA*

MY 50 YEARS IN MEMS

WEDNESDAY, 22 JANUARY — 08:15 (Room 301)



Plenary Presentation III

Han Chung – *i3system, KOREA*

HIGH-RESOLUTION UNCOOLED INFRARED SENSORS: INNOVATIONS IN 3D MEMS TECHNOLOGY FOR MILITARY USE

THURSDAY, 23 JANUARY — 08:15 (Room 304a)



Plenary Presentation IV

Sabeth Verpoorte – *University of Groningen, NETHERLANDS*

WILL ORGAN-ON-A-CHIP SURVIVE THE TEST OF TIME?

MONDAY, 20 JANUARY — 13:05



Session IIIb – Biomedical Sensing

Room 304b

MICROMACHINED SILICA RESONATORS
FOR BIOSENSING APPLICATIONS

Srinivas Tadigadapa

Northeastern University, USA

MONDAY, 20 JANUARY — 14:10



Session IVa – 3D MEMS

Room 304a

3D PRINTED MEMS

Frank Niklaus

KTH Royal Institute of Technology, SWEDEN

TUESDAY, 21 JANUARY — 15:00



Session VIIIa – Metrology Using MEMS

Room 304b

EMERGING TECHNOLOGY FOR THE
BIOHYBRID ROBOTICS

Shoji Takeuchi

University of Tokyo, JAPAN

WEDNESDAY, 22 JANUARY — 14:10



Session XIIb – Nano Material

Room 304b

CARBON NANOTUBES AS CONTACT
MATERIAL FOR MEMS: ENHANCING
SENSITIVITY, DURABILITY,
AND FLEXIBILITY

Jongbaeg Kim

Yonsei University, KOREA

TUESDAY, 21 JANUARY

Hall S2, First Floor



Session I

14:20 – 14:35

**ENABLING ON-CHIP 3D MAGNETIC FIELD
DETECTION WITH HALL EFFECT SENSORS**

Jacopo Ruggeri

Delft University of Technology, NETHERLANDS



Session I

14:35 – 14:50

**CARBON NANOTUBE RESONATOR
RESEARCH**

Morten Vollmann

ETH Zürich, SWITZERLAND

WEDNESDAY, 22 JANUARY

Hall S2, First Floor



Session II

16:40 – 16:55

**TOWARDS TACTILE SENSING HUB VIA
CMOS-MEMS PLATFORM: EFFECT OF
CONTACT INTERFACE MATERIAL AND
COIL TURNS ON THE PERFORMANCE
OF INDUCTIVE TACTILE SENSORS**

Fuchi Shih

National Tsing Hua University, TAIWAN



Session II

16:55 – 17:10

**FROM MOTION TO MEDICINE:
TRIBOELECTRIC NANOGENERATORS
IN NEXT-GEN HEALTHCARE AND
HUMAN-MACHINE INTERACTION**

Kumar Shrestha

Kwangwoon University, KOREA

THE 2025
 IEEE
Robert Bosch
MICRO and NANO ELECTRO MECHANICAL SYSTEMS
AWARD



The Robert Bosch Micro and Nano Electro Mechanical Systems Award was established by the IEEE Electron Devices Society in 2014 to recognize and honor advances in the invention, design, and/or fabrication of micro- or nano-electromechanical systems and/or devices.

The 2025 Bosch Award will be presented on
Monday, 20 January at 08:25.

Gwo-Bin Lee

For Contributions to Micro- and Nano-Fluidic MEMS Technologies for Biomedical Applications

Prof. Gwo-Bin Lee received his B.S. and M.S. degrees in Department of Mechanical Engineering from National Taiwan University in 1989 and 1991, respectively. He received his Ph.D. in Mechanical & Aerospace Engineering from University of California, Los Angeles (UCLA), USA in 1998 with a major on micro-electro-mechanical-systems (MEMS). He is currently a Chair Professor in Department of Power Mechanical Engineering at National Tsing Hua University, Taiwan. His research interests lie on nano-biotechnology, micro/nanofluidics and their biomedical applications.

His most significant contribution lies in his pioneering work on integrating micro/nano-fluidic systems to advance SELEX (Systematic Evolution of Ligands by Exponential Enrichment) technology, which enables the selection of high-affinity aptamers capable of binding with precision to specific targets such as proteins, small molecules, cells, and even viruses. These on-chip SELEX-derived aptamers have served as highly sensitive diagnostic tools for detecting cancer cells, viruses, and other disease biomarkers. These innovative platforms harness the unique ability of ssDNA to engage with biomolecules, influencing gene expression or blocking disease-related mechanisms. The on-chip SELEX method has emerged as a powerful tool for identifying rare and highly specific molecules from vast biological libraries.

He was an elected Fellow of Society of Theoretical and Applied Mechanics (Taiwan), Chinese Society of Mechanical Engineering (Taiwan), ASME, RSC, IET, IEEE, AIMBE and NAI. He is Editor-in-chief of Microfluidics and Nanofluidics (SCI-indexed). He was joint Editor-in-chief of Micro and Nano Letters (SCI indexed) and Associate Editor-in-chief of IEEE Transactions of Nanotechnology (SCI indexed). He was an elected member of International Academy of Engineering and European Academy of Sciences and Arts.

IEEE Electron Devices Society
with Financial support from
Robert Bosch LLC.



Oral Sessions

Oral sessions will be held in Grand Hall 301, Third Floor, with all parallel concurrent sessions in Conference Room 304, Third Floor. See floor plans at the end of this program.

Posters

Three (3) poster sessions will be held in the Hall S2, First Floor on Monday, Tuesday, and Wednesday. All posters are listed with their assigned number and day that they are on display. Authors will be available for questions during their appointed time. Posters are color coded by day and poster category.

Guide to Understanding Poster Numbering

Each poster is assigned a unique number which clearly indicates when and where the poster is presented.

Poster number: **M01-a**

The first character (i.e. **M**) indicates the day of the Conference:

M = Monday **T** = Tuesday **W** = Wednesday

The second character (i.e. **01**) is the poster board position on the floor plan.

The last character (i.e. **a**) is the poster category that is reflected in the Poster Topic Category chart.

Poster Topic Categories

a - Bio and Medical MEMS

b - Emerging Technologies and New Opportunities for MEMS/NEMS

c - Industry MEMS and Advancing MEMS for Products and Sustainability

d - MEMS & NEMS Materials, Fabrication and Packaging

e - MEMS Actuators and PowerMEMS

f - MEMS Physical and Chemical Sensors

g - MEMS/NEMS for Optical, RF and Electromagnetics

h - Micro- & Nanofluidics

i - Open Posters

SUNDAY AT A GLANCE

12:00-19:00 Conference Registration and Check-In

13:00-17:10 Industry Session (Room 304a)

17:10-19:00 Welcome Reception (Room 305)

SUNDAY

SUNDAY, 19 JANUARY

12:00 – 19:00 Conference Registration and Check-In

Industry Session I – AI for MEMS

Room 304a

13:00 MEMS BEYOND SENSORS

Franz Lärmer
Robert Bosch GmbH, GERMANY

13:25 MEMS SENSORS ENABLING SUSTAINABLE EDGE AI COMPUTING

Marco Ferrera
STMicroelectronics, ITALY

13:50 EDGE INTELLIGENCE FOR MEMS: ENABLING ON-DEVICE SENSOR DATA INTERPRETATION WITH TINYML

Sang Won Lee
TDK SensEI, USA

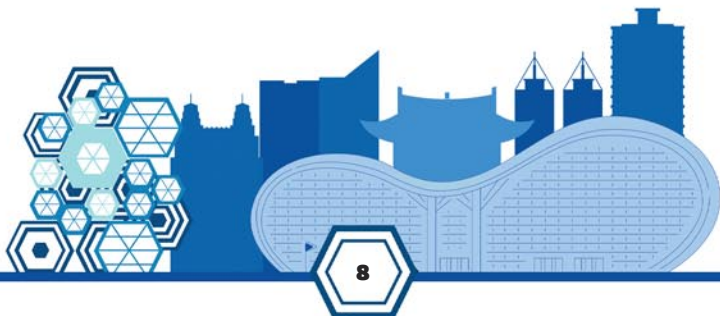
14:15 INNOVATIVE MEMS SENSORS AND AI: POWERED BY AN ULTRA-LOW POWER SENSOR HUB SoC

Jerry Chen
Upbeat Technology, TAIWAN

14:40 SPECTROCHIP X AI - EXPAND THE HORIZON OF SPECTRAL SENSING

Kevin Ko
Spectrochip, TAIWAN

15:05 Break



Industry Session II – MEMS for AI

Room 304a

- 15:30 BRIDGING THE GAP: MEMS AND AI, A PERFECT PARTNERSHIP**
 Jerwei Hsieh
Asia Pacific Microsystems, Inc., TAIWAN

- 15:50 THE X FACTOR IN MEMS INNOVATION: BREAKTHROUGHS ACROSS THREE PRODUCT LINES WITH A SINGLE PLATFORM**
 Chiung-Cheng Lo
xMEMS, USA

- 16:10 AI MEETS MEMS: UNLOCKING THE MEMS INFINITY**
 Mario Kiuchi
Sumitomo Precision Products Co., Ltd., JAPAN

- 16:30 ACCELERATING MEMS PROTOTYPING WITH PIEZOELECTRIC THIN FILM PLATFORMS**
 Zhu Yao
*Agency for Science, Technology and Research (A*STAR), SINGAPORE*

- 16:50 ENHANCING AUTOMOTIVE HMI DESIGN WITH ADVANCED PIEZO-MEMS DEVICES**
 Hao-Yen Tang
UltraSense Systems, USA

- 17:10 Adjourn**

17:10 – 19:00 Welcome Reception (Room 305)

SUNDAY



Kaohsiung Exhibition Center. Source: Kaohsiung City Government

IOP Publishing

Journal of Micromechanics and Microengineering

Journal of Micromechanics and Microengineering (JMM) is a leading journal in its field, covering all aspects of nano- and microelectromechanical systems, devices and structures.

Editor in Chief

Weileun Fang

National Tsing Hua University, Taiwan



JMM is pleased to sponsor the prizes for the best Oral Presentations at this year's IEEE MEMS conference, and welcomes any speaker from MEMS 2025 to submit their next work to the journal.



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MONDAY AT A GLANCE

08:00-08:25	Welcome Address (Room 301)	
08:25-08:45	<ul style="list-style-type: none"> • IEEE Fellows Recognition in the Field of MEMS/NEMS • IEEE EDS Robert Bosch Micro and Nano Electro Mechanical Systems Award 	
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15:10-15:40	Break and Exhibit Inspection (Hall S2)	
17:00	Adjourn for the Day	

MONDAY



Kaohsiung Exhibition Center. Source: Kaohsiung City Government

MONDAY, 20 JANUARY

Welcome Address

Room 301

- 08:00 MEMS 2025 Conference Chairs**
 Hyunjoo “Jenny” Lee, *Korea Advanced Institute of Science and Technology (KAIST), KOREA*
 Sheng-Shian Li, *National Tsing Hua University, TAIWAN*

- **IEEE Fellows Recognition in the Field of MEMS/NEMS**
 - **IEEE EDS Robert Bosch Micro and Nano Electro Mechanical Systems Award**

Room 301

- 08:25 IEEE EDS Robert Bosch Micro and Nano Electro Mechanical Systems Award Recipient**
 Gwo-Bin “Vincent” Lee, *National Tsing Hua University, TAIWAN*

Plenary Presentation I

Chair: Sheng-Shian Li, *National Tsing Hua University, TAIWAN*

Room 301

- 08:45 NAVIGATING THE NEW NORMAL**
Tien Wu
Advanced Semiconductor Engineering, Inc (ASE), TAIWAN

Session I - Medical MEMS

Chair: Maesoon Im, *Korea Institute of Science and Technology (KIST), KOREA*

Room 301

- 09:30 THE FIRST TOOL-CHANNEL TACTILE SENSOR FOR SIMULTANEOUS ACQUISITION OF TACTILE AND FORCE SENSATIONS IN MICRO AND NARROW SPACE UNDER ENDOSCOPIC SURGERY**
 Keisuke Yoshimoto, Takanori Matsui, Kyohei Terao,
 Hideki Kobara, Hidekuni Takao
Kagawa University, JAPAN
- 09:45 A DUAL-DETECTION APPROACH FOR CARDIOTOXICITY SCREENING: UTILIZING NANO SILICON STRAIN SENSOR AND MEA TO MONITOR CONTRACTILITY AND FIELD POTENTIAL IN CARDIOMYOCYTES**
 Haolan Sun, Longlong Li, Dong-Weon Lee
Chonnam University, KOREA
- 10:00 TRIBOELECTRIC MAT MULTIMODAL SYSTEM FOR SLEEP POSE ESTIMATION**
 Jinlong Xu^{1,2}, Xinge Guo^{1,2}, Chengkuo Lee^{1,2}
¹*National University of Singapore, SINGAPORE,*
²*Center for Intelligent Sensors and MEMS (CISM)*

Session I - Medical MEMS (continued)

10:15 **ULTRA-SENSITIVE WIRELESS PRESSURE SENSOR FOR REAL-TIME CARDIOVASCULAR RESTENOSIS MONITORING IN SMART STENTS**
 Lei Wang¹, Nomin-Erdene Oyunbaatar¹, Dong-Su Kim², Jinliang Wei¹, Yun-Jin Jeong³, Heonzoo Lee¹, Su-Hwan Kim⁴, Yonggwon Won¹, Kyeongha Kwon⁴, In-Seok Jeong⁵, Dong-Weon Lee¹
¹Chonnam National University, KOREA, ²Korea Institute of Industrial Technology (KITECH), KOREA, ³Chosun College of Science & Technology, KOREA, ⁴Korea Advanced Institute of Science and Technology (KAIST), KOREA, ⁵Chonnam National University Hospital, KOREA

10:30 **Break & Exhibit Inspection (Hall S2)**

Session II - Electromagnetic MEMS
Chair: Daisuke Yamane, Ritsumeikan University, JAPAN

Room 301

11:00 **DIAMAGNETICALLY LEVITATED AND TRAPPED GRAPHITE MECHANICAL RESONATORS**
 Yunong Wang¹, Alexander Gage¹, Jaesung Lee², Philip X.-L. Feng¹
¹University of Florida, USA, ²University of Central Florida, USA

11:15 **A FLEXIBLE AND ULTRASENSITIVE ARTIFICIAL COMPOUND EYE USING BIONIC MICRO-LENS ARRAY FOR DRONE VISION**
 Jiachuang Wang^{1,2}, Fangyu Zhou^{1,2}, Wenyuan Liu^{1,2}, Nan Qin^{1,2}, Tiger H. Tao^{1,2,3,4,5}
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA, ³Neuroxess Co., Ltd., CHINA, ⁴Guangdong Institute of Intelligence Science and Technology, CHINA, ⁵Tianqiao and Chrissy Chen Institute for Translational Research CHINA,

11:30 **HARNESSING MAGNETIC INTERCONNECTS FOR GENERIC FEEDTHROUGH CANCELLATION IN MEMS RESONATORS**
 Zhong-Wei Lin, Anurag A. Zope, Sheng-Shian Li
 National Tsing Hua University, TAIWAN

11:45 **INTEGRATED RESONANT MICRO-PLATE FOR SIMULTANEOUS DIFFERENTIAL THERMAL ANALYSIS AND THERMOGRAVIMETRIC ANALYSIS**
 Yuhang Yang^{1,2}, Zechun Li^{1,2}, Hao Jia^{1,2}, Pengcheng Xu^{1,2}, Xinxin Li^{1,2}
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA

MEMS Community Announcement

Room 301

12:00 **Clark T.-C. Nguyen, University of California, Berkeley, USA**

12:05 **Lunch and Exhibit Inspection (Hall S2)**

Student Mixer

Central Boulevard - West Lobby Side

- 12:05** **Please join us Monday during lunch for a Student Mixer.**
This opportunity is open to students and postdocs looking to connect and share inspiring ideas. Lunch will be served.

Session IIIa - Inertial MEMS

Chair: Giacomo Langfelder, Politecnico di Milano, ITALY

Room 304a

- 13:05** **MODELING ZERO TEMPERATURE DRIFTS IN GYROSCOPES WITH AND WITHOUT AUTOMATIC QUADRATURE COMPENSATION**
Luca Pileri¹, Marco De Pace¹, Gabriele Gattere²,
Luca Falorni², Giacomo Langfelder¹
¹Politecnico di Milano, ITALY, ²ST Microelectronics, ITALY
- 13:20** **A SELF-POWERED INERTIAL SWITCH WITH ASYMMETRY DOUBLE-WELL POTENTIAL MECHANISM FOR ANTI-FALSE TRIGGERING**
Kai Wang¹, Chao Ren², Ran Zhang¹, Yaling Luo³, Dengyin Zhang¹
¹Nanjing University of Posts and Telecommunications, CHINA,
²Tsinghua University, CHINA, ³Suzhou Zhenlun Spinning Co., Ltd, CHINA
- 13:35** **A NOVEL NEAR-ZERO STIFFNESS MEMS ACCELEROMETER BASED ON DUAL NONLINEAR CURVED BEAMS ANTI-SPRING MECHANISM**
Ruihong Xiong¹, Lihui Jin¹, Xuankai Xu¹, Wenzhen Li¹,
Shihao Du^{2,3}, Yiwei Wang¹, Fang Chen^{2,3}, Tao Wu^{1,2,3,4}
¹ShanghaiTech University, CHINA, ²Chinese Academy of Sciences, CHINA,
³University of Chinese Academy of Sciences, CHINA,
⁴Shanghai Engineering Research Center of Energy Efficient and Custom AI IC, CHINA
- 13:50** **ACHIEVING BELOW 200PPM SCALE FACTOR TEMPERATURE STABILITY IN AN AM GYROSCOPE WITH ON-CHIP STRESS SENSING**
Mehran Hosseini-Pishrobat, Derin Erkan, Erdinc Tatar
Bilkent University, TURKEY

Session IIIb - Biomedical Sensing

Chair: Luyao Lu, George Washington University, USA

Room 304b

- 13:05** **INVITED**
MICROMACHINED SILICA RESONATORS FOR BIOSENSING APPLICATIONS
Vedant Sumaria¹, Hwall Min², Soheil Farazi³, **Srinivas Tadigadapa**³
¹Iota Bioscience, USA, ²Illumina, USA, ³Northeastern University, USA
- 13:35** **MICRODEVICE FOR SYNTHESIS OF BIOGLASS AND ITS BIOACTIVITY STUDY**
Lakshmi Krishnan¹, Abinaya Rajendran¹, Kavitha Govarthanan¹,
Moteo Nagai³, Srabani Kar³, Suresh Rao¹, Tuhin Subhra Santra¹
¹Indian Institute of Technology, Madras, INDIA, ²Toyohashi University of
Technology, JAPAN, ³Indian Institute of Technology, Hyderabad, INDIA

Session IIIb - Biomedical Sensing (continued)

- 13:50 A BIOCHEMICAL SENSOR WITH TUNABLE HIGH SENSITIVITY BASED ON A REFLECTIVE SECONDARY METAGRATING**
Lijun Ma¹, Bingrui Wang², Liye Li¹, Yunhao Cao¹,
Long Rong², Wengang Wu¹
¹Peking University, CHINA, ²Peking University First Hospital, CHINA

14:05 Transition

Session IVa - 3D MEMS

Chair: Tao Li, University of Cincinnati, USA

Room 304a

- 14:10 INVITED
3D PRINTED MEMS**
Po-Han Huang¹, Lee-Lun Lai², Theocharis Iordanidis²,
Shiro Watanabe², Göran Stemme², Niclas Roxhed²,
Kristinn B. Gylfason², **Frank Niklaus**²
¹National Tsing Hua University, Taiwan,
²KTH Royal Institute of Technology, SWEDEN
- 14:40 OPTICAL 3D μ -PRINTED PVDF PIEZOELECTRIC TRAPEZOIDAL-SHAPED MICROGRID FORCE SENSORS**
Nannan Zhou^{1,2}, Huimin Xie¹, Yangxi Zhang¹, Hongrui Ao²
¹Hong Kong Polytechnic University, HONG KONG,
²Harbin Institute of Technology, CHINA
- 14:55 LOW POWER SWITCHING OF A METAL AIR BATTERY TOWARDS EXTENDED LIFETIME**
Farhan Sadik Sium, Steven Tran, Khandaker Reaz Mahmud,
Amirali Nikeghbal, Seungbeom Noh, Carlos Mastrangelo,
Hanseup Kim
University of Utah, USA

Session IVb - In Vitro Assays

Chair: Momoko Kumemura, Kyushu Institute of Technology, JAPAN

Room 304b

- 14:10 ON-CHIP DISASSEMBLING OF CELL-AGGREGATES FOR SEAMLESS SINGLE-CELL ANALYSIS AND HOMOGENEOUS TREATMENT**
Niko Kimura¹, Shigeo S. Sugano², Shinya Sakuma³
¹Tokyo University of Agriculture and Technology, JAPAN, ²National Institute of Advanced Industrial Science and Technology, JAPAN,
³Kyushu University, JAPAN
- 14:25 MICROMETER-SIZED CARBON MESH ELECTRODE-BASED IN-SITU ELECTROCHEMICAL FILTER FOR ENHANCING RELIABILITY OF ELECTROCHEMICAL BIOSENSORS**
Woojae Jeong, Beomsang Kim, Akhsunkhar Khazhmurat,
Heungjoo Shin
Ulsan National Institute of Science and Technology (UNIST), KOREA

Session IVb - In Vitro Assays (continued)

14:40 ARRAYED ELECTRICAL STIMULATION PLATFORM FOR ACCURATE EVALUATION OF CONTRACTILE FORCE OF RING-SHAPED ENGINEERED HEART TISSUE

Daiki Miyata¹, Akari Masuda¹, Gakuto Kagawa¹, Hidenori Tani², Hidetoshi Takahashi¹, Shugo Tohyama², Hiroaki Onoe¹

¹Keio University, JAPAN, ²Fujita Health University, JAPAN

14:55 A RETINA-ELECTRODE INTERFACE FOR LIGHT SENSING AND IMAGE RECOGNITION

Yunxiao Lu¹, Peijie Chen², Zhitao Zhou², Xiaoling Wei², Tiger H. Tao², Lunming Qin¹, Yifei Ye², Liuyang Sun²

¹Shanghai University of Electric Power, CHINA, ²Chinese Academy of Sciences, CHINA³ShanghaiTech University, CHINA, ⁴Neurxess Co.,Ltd, CHINA, ⁵Guangdong Institute of Intelligence Science and Technology, CHINA, ⁶Tianqiao and Chrissy Chen Institute for Translational Research, CHINA

Poster Session I

Hall S2

15:10 Poster Session I

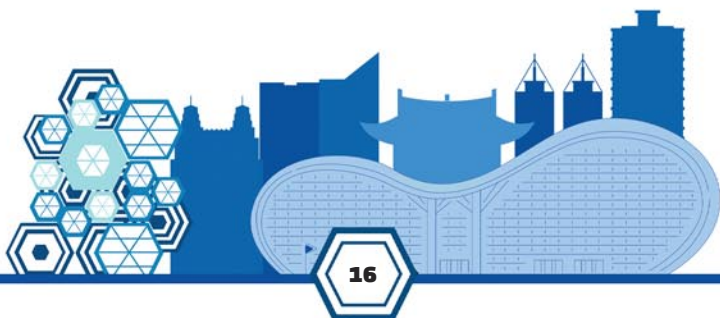
Poster presentations are listed by topic category with their assigned number starting on Page 37.

15:10 Break and Exhibit Inspection (Hall S2)

17:00 Adjourn for the Day



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TUESDAY AT A GLANCE

08:15-09:00	Plenary Presentation II (Room 301) Kurt Petersen – <i>Silicon Valley Band of Angels, USA</i>	
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10:00-10:30	Break and Exhibit Inspection (Hall S2)	
10:30-11:45	Session VI - 3D Manufacturing (Room 301)	
11:45-12:00	MEMS 2026 Announcement (Room 301)	
12:00-13:00	Lunch and Exhibit Inspection (Hall S2)	
13:00-15:00	Poster Session II (Hall S2)	
14:20-14:50	Break and Exhibit Inspection (Hall S2)	
14:20-14:50	Student Led Conference Session I (Hall S2)	
15:00-16:00	Session VIIa - MEMS for Computing (Room 304a)	Session VIIb - Soft MEMS (Room 304b)
16:00-16:05	Transition	
16:05-16:50	Session VIIIa - Metrology Using MEMS (Room 304a)	Session VIIIb - Physical Sensing (Room 304b)
16:50	Adjourn for the day	
18:30-21:00	Conference Banquet (Marriott Hotel)	

TUESDAY



TSRI One-Stop Chip Implementation Service.

TSRI's 0.18 μ m CMOS MEMS Process Platform



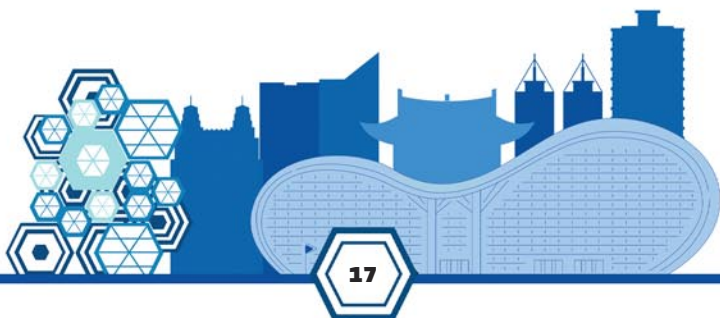
Monolithic CMOS MEMS 3-axis accelerometer, vacuum sensor, resonator (IEDM 2021)

MEMS Measurement Service

Course - CMOS MEMS Sensor Design Concept - CMOS MEMS Chip Implementation Course

Over the past three years, TSRI has provided approximately **180** CMOS MEMS chips taped out annually, along with measurement services for around **200** projects each year.

Future Planning (TBD) - Piezoelectric Platform - Magnetic Platform



TUESDAY, 21 JANUARY

Plenary Presentation II

Chair: Susumu Kaminaga, *Toray Industries, Inc., JAPAN*

Room 301

08:15 MY 50 YEARS IN MEMS
Kurt Petersen
Silicon Valley Band of Angels, USA

Session V - Acoustic MEMS

Chair: Yipeng Lu, *Peking University, CHINA*

Room 301

09:00 MgHf CO-DOPED ALN THIN FILMS TOWARD LOW SIGNAL-TO-NOISE RATIO IN PIEZOELECTRIC MICROMACHINED ULTRASONIC TRANSDUCERS
Hung H. Nguyen^{1,2}, Yosuke Takayama^{1,2}, Hiroki Kuwano^{1,2}
¹*Tohoku University, JAPAN*, ²*Sendai Smart Machines Co., Ltd., JAPAN*

09:15 SINGLE-BIAS DUAL-MODE CMUT ARRAY UTILIZING PRE-SNAPBACK REGION FOR ACOUSTIC HOLOGRAM
Seyoung Park, Geon Kook, Chaerin Oh, Sangho Bang, Hyunjoo J. Lee
Korea Advanced Institute of Science and Technology (KAIST), KOREA

09:30 DEVELOPMENT OF PMUT LINEAR ARRAY INCLUDED WITH FRESNEL ZONE PLATE FOCUSING FUNCTION
Tatsuya Shimoyama, Akihiko Teshigahara, Shinya Yoshida
Shibaura Institute of Technology, JAPAN

09:45 DUAL-ELECTRODE SC0.3AL0.7N PMUT WITH ULTRA-HIGH OUTPUT PRESSURE FOR LONG DISTANCE RANGING
Qing Xin Zhang¹, Peter Hyun Kee Chang¹, Merugu Srinivas¹, Domenico Giusti³, Alberto Leotti², Yul Koh¹, Yao Zhu¹
¹*Agency for Science, Technology and Research (A*STAR), SINGAPORE*, ²*STMicroelectronics, SINGAPORE*, ³*STMicroelectronics, ITALY*

10:00 Break and Exhibit Inspection (Hall S2)

Session VI - 3D Manufacturing

Chair: Jerwei Hsieh, *Asia Pacific Microsystems, Inc., TAIWAN*

Room 301

10:30 SELF-ASSEMBLED HIERARCHICAL NANOPOROUS STRUCTURES FOR DURABLE LUBRICANT-INFUSED SURFACES
Joowon Lim, Geonho Lee, Beomsu Kim, Sueng Yoon Lee, Dohyun Lim, Junho Oh, Won Chul Lee
Hanyang University, KOREA

10:45 SELECTIVE FORMATION OF LASER-INDUCED GRAPHENE (LIG) ADJACENT TO 3D METAL ELECTRODE FOR MINIATURIZED LIG-SENSOR APPLICATION
Yoo-Kyum Shin, Mijeong Kang, Min-Ho Seo
Pusan National University, KOREA

Session VI - 3D Manufacturing (continued)

- 11:00 DLP 3D-PRINTED NANOGENERATORS: RAPID AND ROBUST FABRICATION POLYMERIC MICROSTRUCTURE NANOGENERATOR FOR PORTABLE ENERGY HARVESTING AND SELF-POWERED SENSORS**
Chen-Fang Sun, Muhammad Faizul Zaki, Pin-Chuan Chen
National Taiwan University of Science and Technology, TAIWAN
- 11:15 SEQUENTIAL EXPOSURE DIGITAL LIGHT PROCESSING (SDLP) 3D PRINTING FOR HIERARCHICAL MICROSTRUCTURE TACTILE SENSORS ENABLING ULTRA HIGH-SENSITIVITY, MULTIAXIAL FORCES DETECTION AND LOW CROSS-TALK**
Muhammad Faizul Zaki, Pin-Chuan Chen, Adhimoorthy Saravanan, Bohr-Ran Huang
National Taiwan University of Science and Technology, TAIWAN
- 11:30 MULTILAYERED ON-LENS INDUCTOR FOR EFFICIENT WIRELESS POWERING**
Khandaker Reaz Mahmud, Farhan Sadik Sium, Seungbeom Noh, Ashrafuzzaman Bulbul, Carlos H. Mastrangelo, Hanseup Kim
University of Utah, USA

MEMS 2026 Announcement

Room 301

- 11:45 Conference Chairs**
Andreu Llobera, Silicon Austria Labs, AUSTRIA
Ashwin Seshia, University of Cambridge, UK

- 12:05 Lunch and Exhibit Inspection (Hall S2)**

Poster Session II

Hall S2

- 13:00 Poster Session II**
Poster presentations are listed by topic category with their assigned number starting on Page 37.

- 14:20 Break and Exhibit Inspection (Hall S2)**

Student Led Conference Session I

Chairs: Subeen Kim, Korea Advanced Institute of Science & Technology (KAIST), KOREA & Lee-Lun Lai, KTH Royal Institute of Technology, SWEDEN

Hall S2

- 14:20 ENABLING ON-CHIP 3D MAGNETIC FIELD DETECTION WITH HALL EFFECT SENSORS**
Jacopo Ruggeri, Karen M. Dowling
Delft University of Technology, NETHERLANDS
- 14:35 CARBON NANOTUBE RESONATOR RESEARCH**
Morten Vollmann
ETH Zurich, SWITZERLAND

Session VIIa - MEMS for Computing
 Chair: Kristinn Gylfason, *KTH Royal Institute of Technology, SWEDEN*

Room 304a

- 15:00 CMOS-MEMS PHYSICAL UNCLONABLE FUNCTIONS BASED ON UNBALANCED BIMODAL FREQUENCY COMBS**
 Ting-Yi Chen, Wei-Chang Li
National Taiwan University, TAIWAN
- 15:15 MICROELECTROMECHANICAL LOGIC DEVICE ENABLED BY TUNABLE TORSIONAL RESONATOR WITH LAYERED INDUCTOR**
 Yohan Jung¹, Eunhwan Jo², Jongbaeg Kim¹
¹*Yonsei University, KOREA*, ²*Kumoh National Institute of Technology, KOREA*
- 15:30 PROGRAMMABLE CONNECTED 2D NETWORK OF BISTABLE ELEMENTS FOR MEMS ISING MACHINE**
 Shun Yasunaga, Motohiko Ezawa, Yoshio Mita
University of Tokyo, JAPAN
- 15:45 NANOPHOTONIC EDGE COMPUTING SYSTEM FOR ULTRA-LOW LATENCY HUMAN-MACHINE INTERFACE**
 Zhihao Ren^{1,2}, Zixuan Zhang¹, Yangyang Zhuge¹, Zian Xiao^{1,2}, Siyu Xu¹, Jingkai Zhou¹, Chengkuo Lee^{1,2}
¹*National University of Singapore, SINGAPORE*, ²*National Centre for Advanced Integrated Photonics (NCAIP), SINGAPORE*

Session VIIb - Soft MEMS
 Chair: Hiroaki Onoe, *Keio University, JAPAN*

Room 304b

- 15:00 INVITED**
EMERGING TECHNOLOGY FOR THE BIOHYBRID ROBOTICS
Shoji Takeuchi^{1,2}
¹*University of Tokyo, JAPAN*, ²*Kanagawa Institute of Industrial Science and Technology (KISTEC), JAPAN*
- 15:30 A BIFUNCTIONAL ORGANOHYDROGEL-BASED TRIBOELECTRIC STRAIN SENSING GLOVE FOR SIGN LANGUAGE INTERPRETATION AND HUMAN-MACHINE INTERFACING**
 Shital Sharma, Gagan Bahadur Pradhan, Trilochan Bhatta, Jae Yeong Park
Kwangwoon University, KOREA
- 15:45 A DIRECT CURRENT TRIBOVOLTAIC NANOGENERATOR-DRIVEN SELF-CHARGING SUPERCAPACITOR FOR PREVENTING STRAIN INJURY**
 Kumar Shrestha, Gagan Bahadur Pradhan, Jae Yeong Park
Kwangwoon University, KOREA

16:00 Transition

Session VIIIa - Metrology Using MEMS

Chair: Erdinc Tatar, *Bilkent University, TURKEY*

Room 304a

- 16:05 LIQUID MIXTURE ANALYSIS BY SIMULTANEOUS PROPERTIES MEASUREMENTS UNDER TEMPERATURE MODULATION AND DEEP LEARNING**
Juhee Ko, Jungchul Lee
Korea Advanced Institute of Science and Technology (KAIST), KOREA
- 16:20 INLINE MICROFLUIDIC THERMAL CONDUCTIVITY SENSOR USING A SUSPENDED SILICON HEATER**
Maarten J.S. Bonnema¹, Job Harbers¹, Yaxiang Zeng¹, Jarno Groenesteijn², Remco J. Wiegierink¹, Joost C. Lötters¹
¹*University of Twente, NETHERLANDS*,
²*Bronkhorst High-Tech B.V., NETHERLANDS*
- 16:35 DETERMINING ACTIVATION ENERGY OF AMMONIUM SALTS DECOMPOSITION USING MEMS THERMOPILE-BASED DIFFERENTIAL SCANNING CALORIMETRY (DSC)**
Zechun Li^{1,2}, Shaokui Tan^{1,3}, Ming Li^{1,2}, Yuhang Yang^{1,2}, Haozhi Zhang^{1,2}, Pengcheng Xu^{1,2}, Xinxin Li^{1,2}
¹*Chinese Academy of Sciences (CAS), CHINA*, ²*University of Chinese Academy of Sciences, CHINA*, ³*Shanghai Normal University, CHINA*

TUESDAY

Session VIIIb - Physical Sensing

Chair: Yao Zhu, *Institute of Microelectronics (IME), A*STAR, SINGAPORE*

Room 304b

- 16:05 ENHANCED QUANTUM TEMPERATURE SENSING VIA MICROFLUIDIC-ASSISTED ASSEMBLY OF FLUORESCENT NANODIAMONDS FOR TEMPERATURE MAPPING APPLICATION**
Keita Saikawa¹, Zetsu Masaya¹, Daiki Ueshima¹, Taiichi Shikama¹, Ken-ichiro Kamei^{1,2}, Osamu Tabata³, Yoshikazu Hirai¹
¹*Kyoto University, JAPAN*, ²*New York University, Abu Dhabi, UAE*,
³*Kyoto University of Advanced Science, JAPAN*
- 16:20 FRICTION JOINTING OF DISTRIBUTED RIGID CAPACITORS TO STRETCHABLE LIQUID METAL COIL FOR FULL-BODY WIRELESS CHARGING CLOTHING**
Takashi Sato¹, Shinto Watanabe², Ryo Takahashi³, Wakako Yukita³, Tomoyuki Yokota³, Takao Someya³, Yoshihito Kawahara³, Eiji Iwase², Junya Kurumida¹
¹*National Institute of Advanced Industrial Science and Technology (AIST), JAPAN*, ²*Waseda University, JAPAN*, ³*The University of Tokyo, JAPAN*
- 16:35 AN ANNULAR SLOTS BACK ISLAND MEMS HYDROPHONE WITH ULTRA-HIGH SENSITIVITY AT LOW FREQUENCY**
Lixuan Li, Zhiyong Hu, Tao Ruan, Zhiyue Yang, Hanshuo Liu, Fangtao Kuang, Bin Yang, Jingquan Liu
Shanghai Jiao Tong University, CHINA

16:50 Adourn for the Day

Conference Banquet

Marriott Hotel

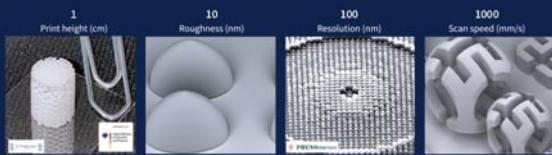
18:30 – Join us for a memorable evening of networking with colleagues.

21:00 This event is included in your registration. Guest tickets may be purchased.

MPO 100



ADVANCED TWO-PHOTON POLYMERIZATION TOOL FOR 3D LITHOGRAPHY AND MICROPRINTING



Design by Axel Heiligenstein et al. Grant FAZ: 23490480

Grant No 730278**



TUESDAY

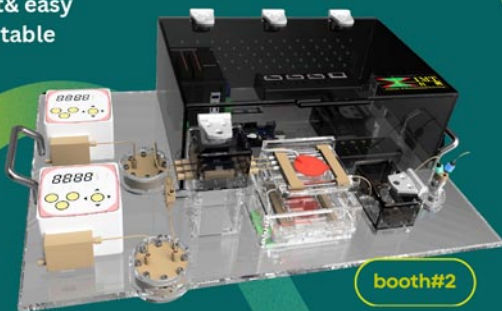


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TUESDAY

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DISCOVER MORE

Spectra Processing Unit **spectrochip**



SPU-M100



Features

- USB connector to PC / Mac
- USB 3.0 compliant
- Plug and play
- Compact
- Open-source imaging software
- Compatible for all OS
- Broad wavelength range
- High spectral resolution
- Real time monitor
- Diverse applications (Optics, Medical...etc)

Application Examples

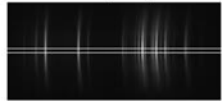
Emission Spectrum	Application
<p>PC ← USB → SPU ← Light Source</p>	<ul style="list-style-type: none"> • LED and Laser Testing • Fluorescent Material
Transmission Spectrum	Application
<p>SPU ← Sample ← Light Source</p>	<ul style="list-style-type: none"> • Water Quality Analysis • Glass and Transparent Material Inspection • Biomedical Analysis
Reflection Spectrum	Application
<p>SPU ← Sample ← Light Source</p>	<ul style="list-style-type: none"> • Food Safety and Quality Inspection • Optical Coating and Thin Film Analysis • Surface Defect Detection

Model Number	SPU-M100
Wavelength range	300 ~ 1000 nm
Spectral Resolution	5 nm
Spectral Accuracy	+/- 0.375 nm
Stray light	0.04 %
Image sensor	AR0144 Mono
A/D Conversion	12 bits
SNR _{max}	6000 (38 dB)
Optical connector*1	SMA905 or Direct connect
Exposure time	2 ms ~ 900 ms
Gain	1 ~ 30 Level
Connector type	USB Type-C
Dimensions (W×D×H) / Weight (module + holder)	53.3 x 38 x 13.31 mm ³ / 53 g

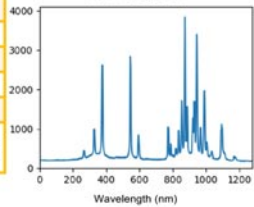
*1 Switchable to other types of optical connectors.
*2 Depending on system performance.

Illustration

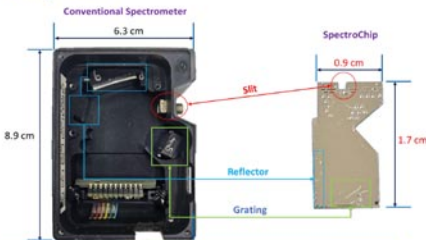
High sensitive detection of atomic spectrum from Hg-Ar light source



Real Time Spectrum



Optical Configuration



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TUESDAY

WEDNESDAY AT A GLANCE

08:15-09:00	Plenary Presentation III (Room 301) Han Chung – <i>i3system, KOREA</i>	
09:00-10:00	Session IX - Resonators (Room 301)	
10:00-10:30	Break and Exhibit Inspection (Hall S2)	
10:30-11:45	Session X - Mechanical Cell Manipulation (Room 301)	
11:45-13:00	Lunch and Exhibit Inspection (Hall S2)	
11:45-13:00	Women in Engineering Networking Luncheon (Central Boulevard – West Lobby Side)	
13:00-14:00	Session XIa - Neural Interface I (Room 304a)	Session XIb - Biomedical Ultrasound (Room 304b)
14:00-14:10	Transition	
14:10-15:10	Session XIIa - Neural Interface II (Room 304a)	Session XIIb - Nano Material (Room 304b)
15:10-17:10	Poster Session III (Hall S2)	
16:40-17:10	Break and Exhibit Inspection (Hall S2)	
16:40-17:10	Student Led Conference Session II (Hall S2)	
17:10	Adjourn for the day	
18:00-20:30	Reunion and Networking Night (Sunset Beach)	

WEDNESDAY



Kaohsiung – Sidiogangshan Skywalk Park. Source: Kaohsiung City Government

WEDNESDAY, 22 JANUARY

Plenary Presentation III

Chair: Hyunjoo "Jenny" Lee,

Korea Advanced Institute of Science and Technology (KAIST), KOREA

Room 301

- 08:15 HIGH-RESOLUTION UNCOOLED INFRARED SENSORS: INNOVATIONS IN 3D MEMS TECHNOLOGY FOR MILITARY USE**
Han Chung, Myungho Kwon, Sang-gu Kang
i3system, KOREA

Session IX - Resonators

Chair: Ashwin Seshia, University of Cambridge, UK

Room 301

- 09:00 A QUICK-SETTLING ENHANCEMENT-MODE RESOSWITCH**
 Nilabh Basu, Chun-Pu Tsai, Ting-Yi Chen, Wei-Chang Li
National Taiwan University, TAIWAN
- 09:15 A NOVEL ELECTROSTATIC FREQUENCY TUNING MECHANISM BASED ON A VERTICALLY COUPLED CMOS-MEMS RESONATOR**
 Wei-Hsiang Hsu¹, Hung-Yu Chen², Zhong-Wei Lin¹, Sheng-Shian Li¹
¹*National Tsing Hua University, TAIWAN,*
²*University of California, Berkeley, USA*
- 09:30 APPROACHING ~0.1ppb FREQUENCY STABILITY IN ~11MHZ AIN-ON-SI DUAL-RING BULK ACOUSTIC WAVE MEMS RESONATOR**
 Connor A. Watkins¹, Tahmid Kaisar¹,
 Mina Rais-Zadeh², Philip X.-L. Feng¹
¹*University of Florida, USA,* ²*California Institute of Technology, USA*
- 09:45 ULTRA-STABLE MEMS CLOCK WITH 53 PARTS-PER-TRILLION FRACTIONAL FREQUENCY STABILITY AT 8 HOURS**
 Jintark Kim¹, Jie Yan¹, Rakibul Islam¹, Jiheng Jing¹, Jiawei Yang²,
 Gabrielle Vukasin², Ryan Kwon², Saurabh Saxena^{1,3},
 Thomas W. Kenny², Pavan K. Hanumolu¹, Gaurav Bahl¹
¹*University of Illinois, Urbana-Champaign, USA,* ²*Stanford University, USA,*
³*Indian Institute of Technology, INDIA*

- 10:00 Break and Exhibit Inspection (Hall S2)**

Session X - Mechanical Cell Manipulation

Chair: Seokheun "Sean" Choi,

State University of New York, Binghamton, USA

Room 301

- 10:30 FIN THRUSTER ON ACOUSTIC RESONATOR (FTAR) FOR MICRO SWIMMING ROBOTS**
 Wenbo Li, Sung Kwon Cho
University of Pittsburgh, USA

WEDNESDAY

Session X - Mechanical Cell Manipulation (continued)

- 10:45 A CELL-SQUEEZING MECHANOPORATION DEVICE FOR INTRACELLULAR DELIVERY**
 Pulasta Chakrabarty¹, Muhammad Ahtsham Iqbal², Ammar Ghous², Srikanth Vedantam¹, Moeto Nagai², Tuhin Subhra Santra¹
¹Indian Institute of Technology, Madras, INDIA,
²Toyohashi University of Technology, JAPAN
- 11:00 PARALLEL PRODUCTION OF UNIFORM ARTIFICIAL CELL AGGREGATES USING VIBRATION-INDUCED FLOW**
 Yui Katsumata, Zhitai Huang, Ryuhei Takata, Reiko Sato, Mamiko Tsugane, Hiroaki Suzuki
 Chuo University, JAPAN
- 11:15 CONTINUOUSLY VARIABLE ON-CHIP FLOW SWITCHER UTILIZING VORTEX GENERATIONS**
 Makoto Saito, Yoko Yamanishi, Shinya Sakuma
 Kyushu University, JAPAN
- 11:30 3D-MICROPRINTED MICROFLUIDIC SCAFFOLDS AND THE RAPID SEEDING STRATEGY FOR ORGAN-ON-A-CHIP APPLICATIONS**
 Chen-Yu Chen, Xin Xu, Ryan D. Sochol, William E. Bentley
 University of Maryland, USA

11:45 Lunch and Exhibit Inspection (Hall S2)

Women in Engineering Networking Luncheon

Central Boulevard - West Lobby Side

- 11:45 Join us to connect with Women in MEMS for career development.**
 Open to all conference attendees. Lunch will be served.

Session XIa - Neural Interface I

Chair: Tuhin Subhra Santra, Indian Institute of Technology, Madras, INDIA

Room 304a

- 13:00 SELF-ASSEMBLED ULTRA-FLEXIBLE MESH PROBES FOR STABLE NEURAL RECORDINGS**
 Kejun Tu, Longchun Wang, Bin Yang, Jingquan Liu
 Shanghai Jiao Tong University, CHINA
- 13:15 A MEMS-BASED FLEXIBLE BIDIRECTIONAL MULTIREGION NEURAL INTERFACE FOR OLFACTORY AUGMENTATION**
 Jizhi Liang^{1,2}, Hailang He^{1,2}, Yuxin Liu¹, Xiaoling Wei^{1,2}, Liuyang Sun^{1,2}, Tiger H. Tao^{1,2,3,4,5,6}, Zhitao Zhou^{1,2}
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA, ³Neuroxess Co., Ltd., CHINA, ⁴ShanghaiTech, CHINA, ⁵Guangdong Institute of Intelligence Science and Technology, CHINA, ⁶Tianqiao and Chrissy Chen Institute for Translational Research, CHINA

Session XIa - Neural Interface I (continued)

- 13:30 A CEREBRAL COMPLIANCE ECG MICROELECTRODE WITH ADAPTIVE 3D UNTETHERED STRUCTURES FOR ENHANCED NEURAL RECORDING**
 Jingjing An, Longchun Wang, Kejun Tu, Mengfei Xu, Zixing Li, Haoyuan Chen, Ning Wei, Bin Yang, Jingquan Liu
Shanghai Jiao Tong University, CHINA
- 13:45 AN IMPLANTABLE NANO-ELECTRODE FOR SIMULTANEOUS IN-SITU SELF-REFERENCING, DRUG DELIVERY, AND RELIABLE FIXED-POINT RECORDING WITHIN A SINGLE NEURON**
 Zhiyuan Du¹, Qingda Xu¹, Ye Xi¹, Mengfei Xu¹, Jiawei Cao¹, Xiantao Zhu¹, Quan Peng¹, Xiuyan Li¹, Xiaolin Wang¹, Bin Yang¹, Zhihong Li², Jingquan Liu¹
¹Shanghai Jiao Tong University, CHINA, ²Peking University, CHINA

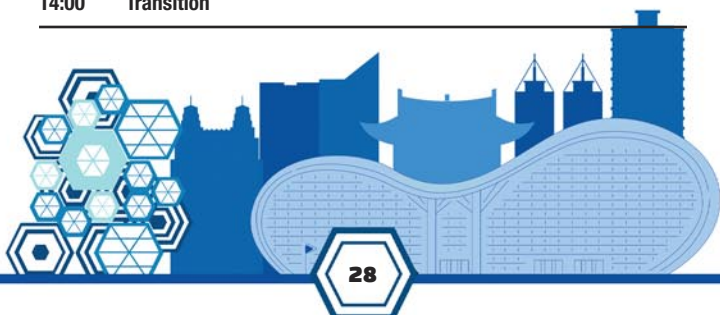
Session XIb - Biomedical Ultrasound

Chair: **Yansong Yang**, *Hong Kong University of Science and Technology (HKUST), HONG KONG*

Room 304b

- 13:00 BONE-SHAPE PMUTS WITH ENHANCED BANDWIDTH FOR DOPPLER BLOOD FLOW DETECTION**
 Kai Yang, Lei Zhao, Yexing Fang, Jiao Xia, Bowen Sheng, Haixia Zhang, Yipeng Lu
Peking University, CHINA
- 13:15 ALIGNMENT-FREE, NON-INVASIVE BLOOD VESSEL MONITORING BY PIEZOELECTRIC MICROMACHINED ULTRASONIC TRANSDUCERS**
 Fan Xia, Yande Peng, Wei Ji, Gurnoor Saini, Yen-Chen Wang, Aalaya Wudaru, Xiaoyang Yu, Mingze Luo, Ariane De Guzman, Zihan Wang, Yuguang Yuan, Jun-Chau Chien, Liwei Lin
University of California, Berkeley, USA
- 13:30 TWO-DIMENSIONAL ULTRASOUND IMAGING USING SINGLE TRANSDUCER PIXEL BASED ON SPATIAL-SPECTRUM CORRELATION METHOD**
 Jinghan Gan, Aocheng Bao, Chong Yang, Yexing Fang, Junhao Wang, Jiao Xia, Bowen Sheng, Yipeng Lu
Peking University, CHINA
- 13:45 MULTIELEMENT SELF-FOCUSING PIEZOELECTRIC MICRO-MACHINED TRANSDUCER FOR CROSS-TISSUE ULTRASONIC STIMULATION**
 Xingyu Bai, Liyun Zhen, Lihan Yu, Meng Cui, Yiqing Shao, Jingquan Liu, Bin Yang
Shanghai Jiao Tong University, CHINA

14:00 Transition



Session XIIa - Neural Interface II
Chair: Sophie Giroud, CEA-LETI, FRANCE

Room 304a

- 14:10 SELF-ROLLING HIGH CONFORMAL FLEXIBLE ELECTRODE FOR PERIPHERAL NEUROMODULATION AND RECORDING**
Jianbo Jiang^{1,2}, Huiran Yang¹, Ziyi Zhu^{1,2}, Dujuan Zou^{1,2}, Siyuan Ni^{1,2}, Zhengyu Liang^{1,2}, Lirui Yang^{1,2}, Guopei Zhou^{1,4}, Zhitao Zhou^{1,2}, Liuyang Sun^{1,2}, Tiger H. Tao^{1,2,3,5,6,7}, Xiaoling Wei^{1,2}
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA, ³Shanghai Tech University, CHINA, ⁴Wuhan Research Institute of Posts and Telecommunications, CHINA, ⁵Neuroxess Co., Ltd., CHINA, ⁶Guangdong Institute of Intelligence Science and Technology, CHINA, ⁷Tianqiao and Chrissy Chen Institute for Translational Research, CHINA
- 14:25 MULTI-STAGE SEGMENTED MEMS ELECTRODE FOR LAYER-BY-LAYER PULSED FIELD ABLATION IN CARDIAC SURGERY**
Quan Peng, Mengfei Xu, Zilang Song, Zhiyuan Du, Jingjing An, Zixing Li, Yunhe Luo, Kaijie Yang, Bin Yang, Mu Qin, Jingquan Liu
Shanghai Jiao Tong University, CHINA
- 14:40 SILK-BASED SELF-UNFOLDING ELECTRODE ARRAY FOR MINIMALLY-INVASIVE LARGE-SCALE DEEP BRAIN ACTIVITY MONITORING**
Jizhi Liang^{1,2}, Songtao Lai^{1,2}, Xiner Wang^{1,2}, Zhaohan Chen³, Xiaoling Wei^{1,2}, Liuyang Sun^{1,2}, Tiger H. Tao^{1,2,3,4,5,6}, Zhitao Zhou^{1,2}
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA, ³Neuroxess Co., Ltd., CHINA, ⁴ShanghaiTech University, ⁵Guangdong Institute of Intelligence Science and Technology, CHINA, ⁶Tianqiao and Chrissy Chen Institute for Translational Research, CHINA
- 14:55 ONE-STEP LASER-INDUCED DISSOLVABLE PVA MASK FOR 3D SOFT CARBON ELECTRODE ARRAY**
Xuanqi Wang¹, Kai Xue¹, Ruiyu Bai¹, Ye Huang¹, Zimo Zhang¹, Xiaoli You¹, Minghao Wang², Honglong Chang¹, Bowen Ji¹
¹Northwestern Polytechnical University, CHINA, ²Hangzhou Dianzi University, CHINA

WEDNESDAY



Session XIIb - Nano Material
Chair: Andreu Llobera, *Silicon Austria Labs, AUSTRIA*

Room 304a

- 14:10 INVITED**
CARBON NANOTUBES AS CONTACT MATERIAL FOR MEMS: ENHANCING SENSITIVITY, DURABILITY, AND FLEXIBILITY
Kyubin Bae, Sangjun Sim, **Jongbaeg Kim**
Yonsei University, KOREA
- 14:40 GEOMETRICALLY RECONFIGURABLE SILK-BASED ELECTRONIC IMPLANTS**
Siyuan Ni^{1,2}, Ziyi Zhu^{1,2}, Zhiwen Yan³, Zhengyu Liang^{1,2}, Jianbo Jiang^{1,2}, Dujuan Zou^{1,2}, Huiran Yang¹, Zhitao Zhou^{1,2}, Liuyang Sun^{1,2}, Tiger H. Tao^{1,2,4,5,6,7}, Yun Qian³, Xiaoling Wei¹, Keyin Liu¹
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA, ³Jiao Tong University School of Medicine, CHINA, ⁴ShanghaiTech University, CHINA, ⁵Neuroxess Co., Ltd., CHINA, ⁶Guangdong Institute of Intelligence Science and Technology, CHINA, ⁷Tianqiao and Chrissy Chen Institute for Translational Research
- 14:55 THERMOGRAVIMETRIC ANALYSIS OF MOLYBDENUM DITELLURIDE NANOFLLAKE USING INTEGRATED RESONANT MICROCANTILEVERS**
Jun Li^{1,2}, Hao Jia^{1,3}, Ruomeng Guo^{1,2}, Qiaoyuan Yang^{1,3}, Pengcheng Xu^{1,3}, Xinxin Li^{1,3}
¹Chinese Academy of Sciences (CAS), CHINA, ²ShanghaiTech University, CHINA, ³University of Chinese Academy of Sciences, CHINA

Poster Session III

Hall S2

- 15:10 Poster Session III**
Poster presentations are listed by topic category with their assigned number starting on Page 37.
-
- 16:40 Break and Exhibit Inspection (Hall S2)**

Student Led Conference Session II

Chairs: Zhi-Qiang Lee, *National Tsing Hua University, TAIWAN* & Sarah O. Spector, *Massachusetts Institute of Technology, USA*

Hall S2

- 16:40 TOWARDS TACTILE SENSING HUB VIA CMOS-MEMS PLATFORM: EFFECT OF CONTACT INTERFACE MATERIAL AND COIL TURNS ON THE PERFORMANCE OF INDUCTIVE TACTILE SENSORS**
Fuchi Shih, Mei-Feng Lai, Weileun Fang
National Tsing Hua University, TAIWAN
- 16:55 FROM MOTION TO MEDICINE: TRIBOELECTRIC NANOGENERATORS IN NEXT-GEN HEALTHCARE AND HUMAN-MACHINE INTERACTION**
Kumar Shrestha
Kwangwoon University, KOREA
-
- 17:10 Adjourn for the Day**

Reunion and Networking Night

Sunset Beach

- 18:30 –** Join us for the Reunion Networking Night.
20:30 It will be held at the Sunset Beach Resort in Si-Zih Wan, a well-known summer resort in Kaohsiung.



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WEDNESDAY



Dagang Bridge (Great Harbor Bridge) connecting Pier-2 Art Center and Peng-lai commercial harbor in the port of Kaohsiung. By BINGJHEN; AdobeStock

THURSDAY AT A GLANCE

08:15-09:00	Plenary Presentation IV (Room 304a) Sabeth Verpoorte – <i>University of Groningen, NETHERLANDS</i>
09:00-10:00	Session XIII - Innovative Sensor (Room 304a)
10:00-10:30	Break and Exhibit Inspection (Hall S2)
10:30-11:30	Session XIV - Environmental Sensing (Room 304a)
11:30-12:00	Awards Ceremony and Final Remarks (Room 304a)
12:00	Conference Adjourns
13:00-16:50	ASE Kaohsiung Technical Tour

MICROS

LWIR Thermal Imaging Microscope



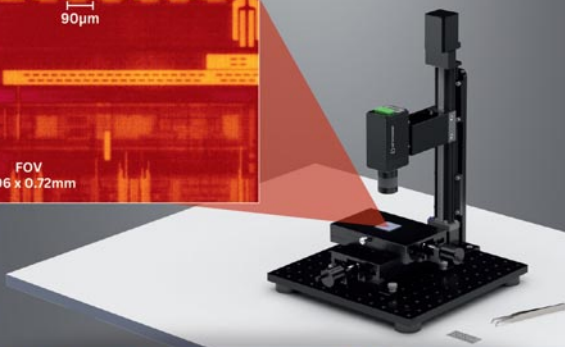
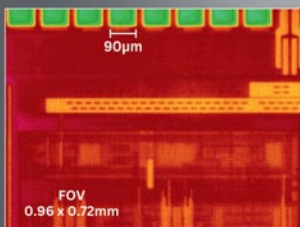
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Applications

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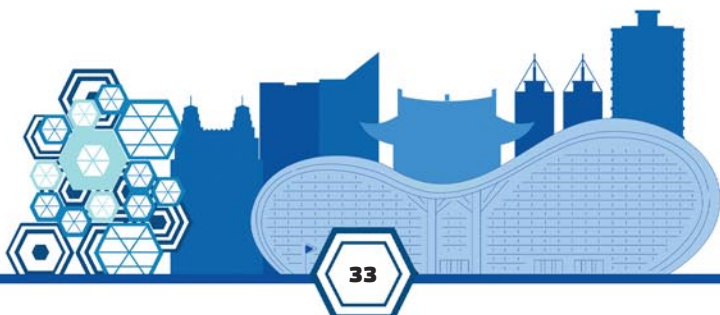


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THURSDAY



THURSDAY, 23 JANUARY

Plenary Presentation IV

Chair: Takehiko Kitamori, *University of Tokyo, JAPAN*

Room 304a

- 08:15 WILL ORGAN-ON-A-CHIP SURVIVE THE TEST OF TIME?**
Sabeth Verpoorte
University of Groningen, NETHERLANDS

Session XIII - Innovative Sensor

Chair: Wei-Chang Li, *National Taiwan University, TAIWAN*

Room 304a

- 09:00 SIMPLE FABRICATION AND INTEGRATION OF 3D ELECTRODES FOR HIGH-SENSITIVITY DROPLET DETECTION**
 Byeolnim Oh¹, Moon Sung Son¹, Jaewon Park³, Kang-Ho Lee², Hyun Soo Kim¹
¹*Kwangwoon University, KOREA*, ²*Korea Institute of Machinery and Materials, KOREA*, ³*Korea University, KOREA*

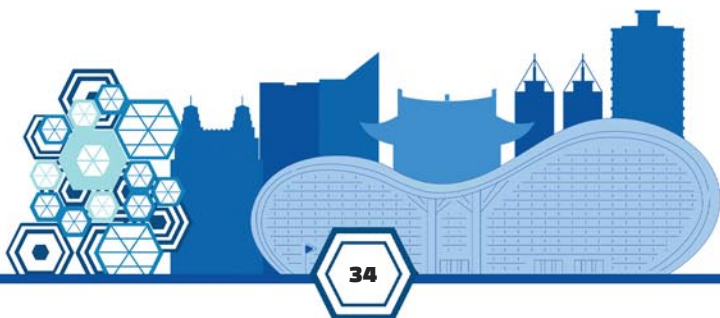
- 09:15 DURABLE AG-COATED MICRO-CRACK VELCRO ELECTRODE FOR HI-FI BIOELECTRIC SIGNALS IN HAIRY AREAS**
 Jun Guo¹, Kang Fu¹, Zimo Zhang¹, Ruiyu Bai¹, Xuanqi Wang¹, Kai Xue¹, Huazhen Chen¹, Le Li¹, Huijing Hu¹, Minghao Wang², Honglong Chang¹, Bowen Ji¹
¹*Northwestern Polytechnical University, CHINA*, ²*Hangzhou Dianzi University, CHINA*

- 09:30 IMPACT OF SKIN SURFACE PH ON INTERSTITIAL FLUID EXTRACTION BY REVERSE IONTOPHORESIS**
 Wangwang Zhu, Haixia Yu, Xi Li, Youhao Liu, Chenxi Jin, Xingguo Zhang, Hao Zheng, Dachao Li, Zhihua Pu
Tianjin University, CHINA

- 09:45 VISUALLY INTELLIGENT DIGITAL MICROFLUIDICS FOR GENERALIZED COLORIMETRIC ASSAYS**
 Zongliang Guo¹, Rongxin Fu¹, Hanzhi Zhang¹, Fenggang Li¹, Siyi Hu², Hang Li¹, Hanbin Ma², Huikai Xie¹, Shuailong Zhang¹
¹*Beijing Institute of Technology, CHINA*, ²*Guangdong ACXEL Micro & Nano Tech Co., Ltd, CHINA*

- 10:00 Break and Exhibit Inspection (Hall S2)**

THURSDAY



Session XIV - Environmental Sensing

Chair: Takashiro Tsukamoto, *Tohoku University, JAPAN*

Room 304a

- 10:30 SIMULTANEOUSLY VOLUMETRIC TEMPERATURE, HUMIDITY AND PRESSURE MONITORING BASED ON ULTRASONIC SIGNALS**
Megan Teng, Peggy Tsao, Liwei Lin
University of California, Berkeley, USA
- 10:45 BATTERY-LESS OUTDOOR FARMING IOT SENSING SYSTEM USING MULTIFUNCTIONAL HYDROGEL ENABLED DIRECT-CURRENT POWERING AND SELF-POWERED LEAF MONITORING CAPABILITY**
Xinge Guo, Luwei Wang, Chengkuo Lee
National University of Singapore, SINGAPORE
- 11:00 INTEGRATED PRECONCENTRATOR-ENHANCED GAS SENSOR FOR LOW POWER DETECTION OF LOW CONCENTRATION TOLUENE**
Jeonghyeop Son¹, Hee-Jin Ko¹, Jaebum Jeong², Jun Young Kim², Jongbaeg Kim¹
¹*Yonsei University, KOREA*, ²*Gyeongsang National University, KOREA*
- 11:15 IC-COMPATIBLE FABRICATION OF UNIFORM WO3 NANOSHEETS FOR ULTRASENSITIVE ON-CHIP HYDROGEN SENSORS**
Jiyong Zhou¹, Jianyou Dai¹, Lei Shan¹, Xiaohong Wang², Sixing Xu¹
¹*Hunan University, CHINA*, ²*Tsinghua University, CHINA*

Awards Ceremony and Final Remarks

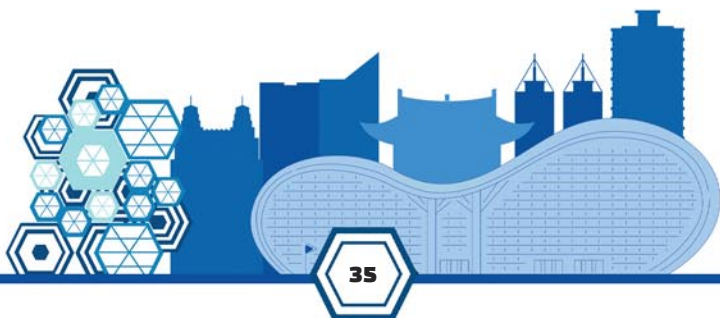
Room 304a

- 11:30 Awards Ceremony**
-
- 11:50 Final Remarks**
-
- 12:00 Conference Adjourns**

ASE Kaohsiung Technical Tour

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- 13:00 – 16:50** Join us for the Technical Tour of ASE in Kaohsiung.



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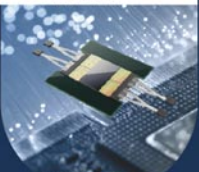
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THURSDAY

Hall S2, First Floor

MONDAY
15:10 – 17:00

TUESDAY
13:00 – 15:00

WEDNESDAY
15:10 – 17:10

POSTER TOPIC CATEGORIES

(last character of poster number)

a - Bio and Medical MEMS

b - Emerging Technologies and New Opportunities for MEMS/NEMS

c - Industry MEMS and Advancing MEMS for Products and Sustainability

d - MEMS & NEMS Materials, Fabrication and Packaging

e - MEMS Actuators and PowerMEMS

f - MEMS Physical & Chemical Sensors

g - MEMS/NEMS for Optical, RF and Electromagnetics

h - Micro- & Nanofluidics

i - Open Posters

See poster floor plans at the end of this program.

a - Bio and Medical MEMS

Biosensors and Bioreactors

M01-a A THIN FILM COIL WITH INTEGRATED ELECTROCHEMICAL SENSOR FOR WIRELESS AND PASSIVE BIOMARKER SENSING

Ruitong Chen, Alexander Baldwin, Emmanuel Ramirez, Ellis Meng
University of Southern California, USA

T01-a CRITICAL SUITABILITY EVALUATION OF CACO-2 CELLS FOR GUT-ON-A-CHIP

Wenhong Zhang¹, Xiatong Pan², Zhipeng Xu³, Jun Chen²,
Junlei Han^{2,4}, Li Wang², Jing Wang¹
¹*Donghua University, CHINA*, ²*Qilu University of Technology, CHINA*,
³*University of Sheffield, UK*, ⁴*Tianjin University, China*

W01-a MACHINE LEARNING-AIDED POLARONIC NANOANTENNAS FOR LABEL-FREE BIOIMAGING OF VIRUS MONOLAYERS

Hong Zhou, Dongxiao Li, Zhihao Ren, Cheng Xu, Chengkuo Lee
National University of Singapore, SINGAPORE

M02-a MACHINE LEARNING-ENHANCED OVERCOUPLED PLASMONIC RESONATORS FOR BIOMOLECULAR DETECTION

Dongxiao Li, Hong Zhou, Zhihao Ren, Cheng Xu, Chengkuo Lee
National University of Singapore, SINGAPORE

Biosensors and Bioreactors

- T02-a** **SENSITIVITY ENHANCEMENT WITH NOISE SUPPRESSION OF SURFACE FUNCTIONALIZATION FOR SILICON NANOWIRE BIOSENSORS**
 Dongqin Chen^{1,2}, Jiushuai Xu¹, Yanzhi Dou¹, Tie Li¹
¹Chinese Academy of Sciences (CAS), CHINA,
²University of Chinese Academy of Sciences, CHINA

a - Bio and Medical MEMS

Devices & Systems for Cellular and Molecular Studies

- W02-a** **AN AUTOMATIC DIVERTER MICROFLUIDIC CHIP WITH DUAL-CHANNEL CONCENTRATION GRADIENT FOR DRUG SCREENING OF HEAD AND NECK TUMOR CELLS**
 Zhimi Zhang^{1,2}, Jingru Liao¹, Xiaolong Ru¹, Guiquan Zhu¹,
 Ling Li², Yuanlin Xia¹, Zhuqing Wang¹
¹Sichuan University, CHINA, ²University of Electronic Science and Technology of China, CHINA
- M03-a** **AN INTEGRATED MICROFLUIDIC SYSTEM FOR mRNA EXTRACTION FROM IN VITRO TRANSCRIBED REACTION MIXTURE BY USING PROBE-COATED MAGNETIC BEADS**
 Swati T. Gurme, Yu-Ting Su, Yi-Da Chung,
 Lily Hui-Ching Wang, Gwo-Bin Lee
 National Tsing Hua University, TAIWAN
- T03-a** **MICRO-FLOWER STRUCTURE ACTIVATED PHOTOPORATION FOR LARGE SIZED BIOMOLECULAR DELIVERY IN CANCER CELLS**
 Ashwini S. Shinde¹, Pallavi Shinde¹, Moeto Nagai²,
 Tuhin Subhra Santra¹, Srabani Kar³
¹Indian Institute of Technology, Madras, INDIA, ²Toyohashi University of Technology, JAPAN, ³Indian Institute of Technology, Hyderabad, INDIA
- W03-a** **MICROENVIRONMENT COMPARTMENTALIZATION FOR OPTIMIZING DIFFERENTIATION OF IPS CELLS**
 Daiki Fukai¹, Yuma Abe¹, Taro Toyoda², Hidekuni Takao¹, Kyohei Terao¹
¹Kagawa University, JAPAN, ²Kyoto University, JAPAN
- M04-a** **SINGLE CELL EJECTION FROM PERIPHERAL BLOOD MONONUCLEAR CELLS (PBMC) INTO OIL-COATED 96-WELL PLATE**
 Kianoush Sadeghian Esfahani, Baptiste Neff, Akash Roy,
 Anik Sengupta, Eun S. Kim
 University of Southern California, USA

a - Bio and Medical MEMS

Flexible and Wearable Devices and Systems

- T04-a** **A FULLY INTEGRATED, FLEXIBLE AND TUNABLE CAPACITIVE STRAIN SENSOR BASED ON MAGNETO-DIELECTRIC FOR HUMAN MOTION MONITORING**
 Mujeeb Yousuf, Pushpapraj Singh
 Indian Institute of Technology, New Delhi, INDIA

Flexible and Wearable Devices and Systems

- W04-a** **A HIGHLY MINIATURIZED, STABLE, BREATHABLE E-SKIN PATCH FOR SKIN-HYDRATION AND ECG MONITORING**
Gagan Bahadur Pradhan, SeongHoon Jeong,
Sudeep Sharma, Jae Yeong Park
Kwangwoon University, KOREA
- M05-a** **A SELF-ASSEMBLED FLEXIBLE STRAIN AND TEMPERATURE SENSOR BASED ON THE MICROSTRUCTURE OF PYRAMIDS WITH HIGH ELASTICITY, TEMPERATURE SENSITIVITY AND WIDE RANGE**
Yangtao Yu¹, Bo Yan¹, Wenbo Cui², Mengqiu Li¹, Chenyuan Li¹,
Faheng Zang¹, Zhuoqing Yang¹
¹*Shanghai Jiao Tong University, CHINA*,
²*Harbin Institute of Technology, CHINA*
- T05-a** **A WEARABLE PAPER-BASED HYBRID ENERGY HARVESTER FROM HUMAN SWEAT AND AMBIENT MOISTURE**
Yang Gao, Seokheun Choi
State University of New York, Binghamton, USA
- W05-a** **A WEARABLE SYSTEM FOR WIRELESS AND MULTIPLEXED MOLECULAR SENSING VIA SOLID MICRONEEDLES**
Emmanuel Ramirez¹, Christopher Larson¹, James J. Yoo¹,
Chelsea Brown², Kevin W. Plaxco², Tod Kippin², Ellis Meng¹
¹*University of Southern California, USA*,
²*University of California, Santa Barbara, USA*
- M06-a** **ARTERIAL PULSE SIGNAL ACQUISITION USING FLEXIBLE SENSING DENSE ARRAY WITH HIGH SPATIAL RESOLUTION**
Yue He^{1,2}, Ke Sun², Fang Wang², Tiger H. Tao², Heng Yang²,
Yi Sun², Quan Wang¹, Xinxin Li²
¹*Jiangsu University, CHINA*, ²*Shanghai Institute of Microsystem and Information Technology, CHINA*
- T06-a** **CONFORMAL ULTRASOUND PATCH FOR REAL-TIME BLOOD FLOW MONITORING**
Taemin Lee¹, Jongcheol Park², Il-seop Kim³, Sangho Bang¹,
Joontaek Jung², Hyunjoo J. Lee¹
¹*Korea Advanced Institute of Science and Technology (KAIST), KOREA*,
²*National NanoFab Center (NNFC), KOREA*, ³*Healcerion Co., Ltd., KOREA*
- W06-a** **ECO-FRIENDLY FABRICATION PROCESS OF FLEXIBLE PIEZOELECTRIC PRESSURE SENSORS: A PATH TO SUSTAINABLE ELECTRONICS**
Mujeeb Yousuf, Sazid Ali, Khanjan Joshi, Pushpapraj Singh
Indian Institute of Technology, Delhi, INDIA
- M07-a** **STRETCHABLE AND SELF-HEALING GRAPHITE/POLYBOROSILOXANE CONDUCTIVE COMPOSITES FOR WEARABLE STRAIN SENSORS**
Guan-Ze Song, Yi-Tsung Su, Kuan-Yu Tu, Lung-Hao Hu, Ching-Te Kuo
National Sun Yat-sen University, TAIWAN

Flexible and Wearable Devices and Systems

- T07-a** **STRUCTURAL AND CONSTITUENT ENGINEERING OF CONDUCTIVE POLYMER COMPOSITES TOWARDS SYNERGETIC MONITORING OF PHYSIOLOGICAL PRESSURE AND ELECTROPHYSIOLOGICAL SIGNALS**
 Wanxin Zhou, Xiaoyu Wang, Yuanlin Xia, Zhuqing Wang
Sichuan University, CHINA
- W07-a** **TACTILE SENSING OF EXTENSOR TENDONS AND NEAR-SENSOR GESTURE RECOGNITION FOR CONTROL OF ROBOTIC HAND**
 Yushen Hu¹, Zhejun Zhang¹, Tengting Lei¹, Man Wong^{1,2}
¹*Hong Kong University of Science and Technology, CHINA,*
²*Guangzhou HKUST Fok Ying Tung Graduate School, CHINA*

a - Bio and Medical MEMS

Manufacturing for Bio- & Medical MEMS

- M08-a** **A SILK-BASED MULTIFUNCTIONAL AND BIDIRECTIONAL NEURAL INTERFACE**
 Xiner Wang^{1,2}, Yan Wang³, Yuxin Liu¹, Xiaoling Wei^{1,2}, Liuyang Sun^{1,2}, Tiger H. Tao^{1,2,4,5,6}, Zhitao Zhou^{1,2}
¹*Chinese Academy of Sciences (CAS), CHINA,* ²*University of Chinese Academy of Sciences, CHINA,* ³*Shanghai Normal University, CHINA,* ⁴*Neuroxess Co., Ltd., CHINA,* ⁵*Guangdong Institute of Intelligence Science and Technology, CHINA,* ⁶*Tianqiao and Chrissy Chen Institute for Translational Research, CHINA*
- T08-a** **BREAKING THE DIMENSION BARRIER: VARIDDEPTH NEUROELECTRODE ARRAY (VD-NEA) ENABLED BY A NOVEL STEREO MASK FOR ACHIEVING ARBITRARY ELECTRODE DEPTH IN NEURAL RECORDING**
 Zhitong Zhang, Zhe Huang, Lexuan Yang, Junshi Li, Yu-Qing Zheng, Zhihong Li
Peking University, CHINA
- W08-a** **ELECTROWETTING-ON-DIELECTRIC-BASED MICROBUBBLE PATTERNING FOR SPATIAL ULTRASOUND MODULATION**
 Subeen Kim, Sangho Bang, Yehhyun Jo, Hyunjoo J. Lee
Korea Advanced Institute of Science and Technology (KAIST), KOREA
- M09-a** **IN-SITU RING ASSEMBLED INNER TUBULAR FABRICATION BY OPTOFLUIDIC MASKLESS LITHOGRAPHY FOR SOFT ROBOTICS AND MEDICAL DEVICES INSPIRED FROM SEGMENT CONSTRUCTION OF SHIELD TUNNEL TECHNOLOGY**
 Yuki Kamiya, Yingzhe Wang, Keisuke Morishima
Osaka University, JAPAN
- T09-a** **MICROFLUIDIC TISSUE BARRIER SENSOR CHIP WITH INTEGRATED MICROELECTRODES AND ULTRATHIN MICROPOROUS MEMBRANE**
 Pratik V. Tawade¹, Hande Aydogmus¹, Lovro Ivancevic¹, Jia-Jun Yeh^{1,2}, Vasiliki Gkouzioti³, Jean-Philippe Frimat³, Jaap den Toonder², Massimo Mastrangeli¹
¹*Delft University of Technology, NETHERLANDS,*
²*Eindhoven University of Technology, NETHERLANDS,*
³*Leiden University Medical Center, NETHERLANDS*

Manufacturing for Bio- & Medical MEMS

- W09-a SILICON-BASED WIRELESS PASSIVE LC MICROSYSTEMS WITH POTENTIAL FOR PULMONARY ARTERY PRESSURE MONITORING**
 Pichao Pan^{1,2}, Li Wang^{1,2}, Min Liu^{1,2}, Xinxin Li^{1,2}
¹Chinese Academy of Sciences, CHINA,
²University of Chinese Academy of Sciences, CHINA

a - Bio and Medical MEMS
Materials for Bio- and Medical MEMS

- M10-a A HIGHLY CATALYTIC ZWITTERIONIC HYDROGEL FOR ELECTROCHEMICAL ENZYMATIC BIOSENSORS**
 Chengcheng Li, Wenjun Li, Wangwang Zhu, Xingguo Zhang,
 Hao Zheng, Zhihua Pu, Dachao Li
 Tianjin University, CHINA
- T10-a DNA-APTAMER INCORPORATED MICROGEL BEADS BY CRYOGENIC PARTICLE FABRICATION**
 Momoka Minami, Satofumi Kato, Hiroaki Onoe
 Keio University, JAPAN
- W10-a PHOTOLUMINESCENT POLYMER FILMS FOR HIGH-SENSITIVITY OXYGEN SENSING IN BIOMEDICAL IMPLANTS**
 Julian A. Singer¹, Anton Geläschus¹, Patrick Kleinschnittger¹,
 Ute Schmidt¹, Matthias Kuhl², Andreas Bahr³
¹Hamburg University of Technology, GERMANY, ²University of Freiburg,
 GERMANY, ³Technische Universität Dresden, GERMANY

a - Bio and Medical MEMS
Medical Microsystems

- M11-a A MEMS-BASED MINIATURIZED WIRELESS FULLY-IMPLANTABLE BRAIN-COMPUTER INTERFACE SYSTEM**
 Zexi Su^{1,2}, Jiaqi Yang^{1,2}, Xiaoling Wei^{1,2}, Liuyang Sun^{1,2},
 Tiger H. Tao^{1,2,3,4,5,6}, Zhitao Zhou^{1,2}
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese
 Academy of Sciences, CHINA, ³ShanghaiTech University, CHINA,
⁴Neuroxess Co., Ltd., CHINA, ⁵Guangdong Institute of Intelligence
 Science and Technology, CHINA, ⁶Tianqiao and Chrissy Chen
 Institute for Translational Research, CHINA
- T11-a A MODIFIED ULTRA-FLEXIBLE NEURAL ELECTRODE FOR LONG-TERM DUAL-MODALITY DETECTION ACROSS MULTIPLE BRAIN REGIONS**
 Guopei Zhou^{1,2}, Xueying Wang^{2,3}, Jianbo Jiang^{2,3}, Dujuan Zou^{2,3},
 Zhengyu Liang^{2,3}, Huiran Yang², Ziyi Zhu², Siyuan Ni^{2,3},
 Mingliang Xu³, Fei He², Liuyang Sun^{2,3}, Zhitao Zhou^{2,3},
 Tiger H. Tao^{2,3,4,5,6}, Xiaoling Wei^{2,3}
¹Wuhan Research Institute of Posts and Telecommunications, CHINA,
²Chinese Academy of Sciences, CHINA, ³University of Chinese Academy
 of Sciences, CHINA, ⁴Neuroxess Co., Ltd. (Jiangxi), CHINA, ⁵Guangdong
 Institute of Intelligence Science and Technology, CHINA, ⁶Tianqiao and
 Chrissy Chen Institute for Translational Research, CHINA

Medical Microsystems

W11-a A SILK-BASED MINIMALLY INVASIVE STENT-ELECTRODE SYSTEM FOR VASOSPASM MONITORING AND IN-SITU TREATMENT

Yihan Diao^{1,2}, Hailang He^{1,2}, Zuyong Fang^{1,2}, Xiaoling Wei^{1,2}, Liuyang Sun^{1,2}, Tiger H. Tao^{1,2,3,4,5,6}, Zhitao Zhou^{1,2}

¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA, ³ShanghaiTech University, CHINA, ⁴Neuroxess Co., Ltd., CHINA, ⁵Guangdong Institute of Intelligence Science and Technology, CHINA, ⁶Tianqiao and Chrissy Chen Institute for Translational Research, CHINA

M12-a BIPOLAR CONCENTRIC RING MICRONEEDLE ARRAY (BCRMA): AN ELECTRICAL STIMULATION ELECTRODE FOR PRECISE MOVEMENT CONTROL

Jiayan Zhang, Dongxu Ma, Zhitong Zhang, Zhongyan Wang, Yuxing Pang, Junshi Li, Zhihong Li
Peking University, CHINA

T12-a DISSOLVABLE SILK FIBROIN MICRONEEDLE (SF μ N) PATCH FOR LONG-ACTING THYROID HORMONE REPLACEMENT THERAPY

Diana V. Rodriguez De Francisco, Edwin Davidson Barahona, Omar S. Cepeda Torres, Swadeshmukul Santra, Swaminathan Rajaraman
University of Central Florida, USA

W12-a HIGHLY SENSITIVE DRIP-PROOF TACTILE ARRAY SENSOR FOR SLIP/GRASP DETECTION UNDER LAPAROSCOPIC SURGERY

Keisuke Yoshimoto¹, Sho Yoshikawa¹, Masao Fujiwara², Kyohei Terao¹, Hidekuni Takao¹

¹Kagawa University, JAPAN, ²Takamatsu Red Cross Hospital, JAPAN

M13-a IN VITRO ELECTRICAL STIMULATION SYSTEM BASED ON STRETCHABLE MICROELECTRODE ARRAY

Yoojeong Kim¹, Byumseok Koh², Kiup Kim¹, Sung Bum Park², Ki Young Kim², Jeong Hyeon Jo^{2,3}, Hyunjoo J. Lee¹

¹Korea Advanced Institute of Science and Technology (KAIST), KOREA, ²Korea Research Institute of Chemical Technology (KRICT), KOREA, ³Chungnam National University, KOREA

T13-A INTRACORTICAL FLEXIBLE MICRONEEDLE NEURAL ELECTRODE (f- μ NEURODE) BASED ON PROJECTION-MICRO-STEREOLITHOGRAPHY (P μ SL) TECHNOLOGY FOR CHRONIC IN-VIVO ELECTROPHYSIOLOGICAL RECORDING

Zhe Huang^{1,4}, Yanran Wang², Junshi Li^{1,4}, Xinyi Ma^{1,4}, Zhitong Zhang^{1,4}, Xiaowen Sun², Jiayan Zhang^{1,4}, Dong Huang³, Bin Yang⁵, Jingquan Liu⁵, Dajun Xing², Zhihong Li^{1,4}

¹Peking University, CHINA, ²Beijing Normal University, CHINA, ³Acimicro Medical Technology Co., Ltd., CHINA, ⁴Beijing Advanced Innovation Center for Integrated Circuits, CHINA, ⁵Shanghai Jiao Tong University, CHINA

Medical Microsystems

- W13-a MEMS-BASED HIGH-DENSITY ULTRA-CONFORMAL μ ECOG ELECTRODE ARRAY FOR REAL-TIME MOTOR DECODING**
 Erda Zhou¹, Changjiang Liu¹, Xiner Wang¹, Xiaoling Wei¹,
 Liuyang Sun¹, Tiger H. Tao^{1,2,3,4,5}, Zhitao Zhou¹
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA, ³Neuroxess Co., Ltd. CHINA, ⁴Guangdong Institute of Intelligence Science and Technology, CHINA, ⁵Tianqiao and Chrissy Chen Institute for Translational Research, CHINA
- M14-a MINIATURE AND WIRELESS ULTRASONIC IMAGING SYSTEM FOR WEARABLE HUMAN CAROTID ARTERY HEALTH MONITORING**
 Lei Zhao, Aocheng Bao, Chong Yang, Junhao Wang,
 Xixin Cao, Yipeng Lu
 Peking University, CHINA
- T14-a MULTIMODAL MEMS MICROWRINKLE ELECTRONICS FOR CARDIAC PULSED FIELD ABLATION AND SENSING**
 Mengfei Xu¹, Quan Peng¹, Ziliang Song¹, Mu Qin¹,
 Yimeng Sun², Zhiyuan Du¹, Kunyu Zheng¹,
 Xiaolin Wang¹, Bin Yang¹, Jingquan Liu¹
¹Shanghai Jiao Tong University, CHINA,
²Shanghai University of Electric Power, CHINA
- W14-a SPRING-LIKE KIRIGAMI MICROELECTRODE ARRAY IN SHAPE MEMORY POLYMER FOR SPONTANEOUS ADAPTATION OF COMPLEX TOPOGRAPHY IN NEURAL IMPLANTS**
 Yuanhao Xu, Stella W. Pang
 City University of Hong Kong, HONG KONG
- M15-a ULTRA-FLEXIBLE HONEYCOMB DEEP BRAIN ELECTRODE FOR RESISTANCE TO BRAIN SHIFT AND EXTERNAL DISTURBANCES**
 Dongyang Wen¹, Kejun Tu¹, Liyun Zhen¹, Bin Yang¹,
 Zhihong Li², Jingquan Liu¹
¹Shanghai Jiao Tong University, CHINA, ²Peking University, CHINA

a - Bio and Medical MEMS

MEMS & BioMEMS for Fighting COVID-19 & Future Pandemic

- T15-a BIOCHEMICAL DETECTION BASED ON NANOPARTICLE INDUCED ULTRASONIC RAYLEIGH SCATTERING**
 Wangyang Zhang, Jiaqian Yang, Haoliang Jia, Tao Liu,
 Yuchen Mao, Lei Ren, Ziwei Chen, Xiaojing Mu
 Chongqing University, CHINA

a - Bio and Medical MEMS

MEMS & BioMEMS for Healthcare and Public Health

- W15-a INTEGRATED MICROFLUIDIC RAPID RESPONSE AND HIGHLY SENSITIVE ELECTROCHEMICAL APTASENSOR FOR SIMULTANEOUS DETECTION OF AFLATOXIN B1 AND DEOXYNIVALENOL**
 Jinlei Wu, Qinghui Jin, Ping Yang, Wanlei Gao,
 Ningbo University, CHINA

MEMS & BioMEMS for Healthcare and Public Health

- M16-a** **A MEMS PRESSURE SENSOR ARRAY FOR SLEEP APNEA RECOGNITION AND MONITORING BASED ON THE PRINCIPLE OF TRADITIONAL CHINESE MEDICINE**
 Lin Qin, Long Cheng, Xianzhang Zeng, Yuanlin Xia, Zhuqing Wang
Sichuan University, CHINA
- T16-a** **AN ARRAY OF SILICON DUAL MICRONEEDLE ELECTRODES INTEGRATED WITH MINI-LEDS FOR ELECTROPHYSIOLOGICAL RECORDING AND SIMULTANEOUS APPLICATION OF ELECTRICAL AND OPTICAL STIMULI TO THE RETINA FOR ARTIFICIAL VISION**
 Seung-Han Chung¹, Chaesung Kim^{2,3}, Yong-Kweon Kim¹, Seung-Ki Lee⁴, Jae-Hyoung Park⁴, Mesoon Im^{2,5,6}
¹Seoul National University, KOREA, ²Korea Institute of Science and Technology, KOREA, ³Korea University, KOREA, ⁴Dankook University, KOREA, ⁵University of Science & Technology, KOREA, ⁶Kyung Hee University, KOREA
- W16-a** **HIGH-RESOLUTION HAIR TEXTURE SENSOR WITH MONOLITHICALLY INTEGRATED GUIDING STRUCTURE FOR REALIZATION OF PRECISE EVALUATION AND SIMPLE OPERATION**
 Gakuto Tanaka¹, Masahito Komatsubara¹, Ryusei Kawagoe¹, Hirotohi Oikaze², Yoshiyasu Kitagawa², Yasunori Matsui², Hidekuni Takao¹
¹Kagawa University, JAPAN, ²Panasonic Corporation, JAPAN
- M17-a** **NONPLANAR WIRELESS DIFFERENTIAL MICROSENSOR FOR INTEGRATION ON INTRAVENOUS CATHETERS FOR THERAPEUTIC DRUG MONITORING AND OTHER APPLICATIONS**
 Jiaxin Jiang¹, Vidya Chidambaran², Tao Li¹
¹University of Cincinnati, USA, ²Cincinnati Children's Hospital Medical Center, USA
- T17-a** **SILICON SOLAR CELL-INTEGRATED FLEXIBLE RETINAL PROSTHESIS FOR ARTIFICIAL VISION**
 Chaesung Kim^{1,2}, Seung-Han Chung³, Yong-Jin Kim⁴, Hyeonhee Roh^{1,2}, Seung-Ki Lee⁵, Yong-Kweon Kim³, Hyung-Min Lee¹, Jae-Hyoung Park⁵, Min-Gu Kang⁴, Maesoon Im^{2,6,7}
¹Korea University, KOREA, ²Korea Institute of Science and Technology, KOREA, ³Seoul National University, KOREA, ⁴Korea Institute of Energy Research, KOREA, ⁵Dankook University, KOREA, ⁶University of Science and Technology, KOREA, ⁷Kyung Hee University, KOREA
- W17-a** **WEARABLE NUCLEAR MAGNETIC RESONANCE SPECTROSCOPY SYSTEM TO DETECT STRESS AND VIRAL BIOMARKERS, AND ILLICIT DRUGS NON-INTRUSIVELY IN VIVO**
 Massood Tabib-Azar, Brian Baker
University of Utah, USA
- W117-a** **A HIGH-DENSITY ELECTROMYOGRAPHY SENSOR BASED ON MEMS E-SKIN FOR DETECTING ACTIVITY OF MOTOR UNITS**
 Yirong Wang, Shuihan Shao, Chunpeng Jiang, Bin Yang, Jingquan Liu
Shanghai JiaoTong University, CHINA

a - Bio and Medical MEMS

Tissue Engineering

- M18-a** **INNOVATIVE STAMP-STRUCTURED ORGAN-ON-A-CHIP PLATFORM FOR VASCULARIZED TUMOR AND COLON MODELS**
Feifan Wang, Chenyang Zhou, Xiaolin Wang
Shanghai Jiao Tong University, CHINA
- T18-a** **TONGUE-LIKE BIOACTUATOR WITH MULTIPLE SKELETAL MUSCLE TISSUES**
Xuankai Gao¹, Kohei Okasaki², Hirono Ohashi², Takeshi Sakurai², Yuya Morimoto¹
¹Waseda University, JAPAN, ²Tokyo University of Agriculture, JAPAN

b - Emerging Technologies & New Opportunities for MEMS/NEMS

Computing Devices and Systems with MEMS/NEMS

- M19-b** **EDGE-COMPUTING ENABLED SI PHOTONICS MULTIMODAL SENSOR WITH INTEGRATED PHOTONIC CONVOLUTIONAL PROCESSOR**
Zian Xiao^{1,2}, Zhihao Ren¹, Yangyang Zhuge¹, Zixuan Zhang¹, Jingkai Zhou¹, Siyu Xu¹, Cheng Xu¹, Bowei Dong³, Chengkuo Lee^{1,2,4}
¹National University of Singapore, SINGAPORE, ²NUS Suzhou Research Institute (NUSRI), SINGAPORE, ³Institute of Microelectronics, SINGAPORE, ⁴National Centre for Advanced Integrated Photonics, SINGAPORE
- T19-b** **HIGH-TEMPERATURE DUAL-RAIL CONTACTLESS MEMS LOGIC FOR INDUSTRIAL EDGE COMPUTING**
Aleksandra Markovic¹, Adrian Laborde¹, Nicolas Mauran¹, Hervé Fanet¹, Gaël Pillonnet², Bernard Legrand¹
¹LAAS-CNRS, FRANCE, ²CEA-Leti, FRANCE
- W18-b** **IMPROVED LEARNING PERFORMANCE IN PHYSICAL RESERVOIR COMPUTING USING COUPLED TRIPLE MEMS NONLINEAR RESONATORS**
Kosuke Shima, Hiroki Takemura, Masaki Shimofuri, Amit Banerjee, Jun Hirotsani, Toshiyuki Tsuchiya
Kyoto University, JAPAN
- M20-b** **NEUROMORPHIC PIEZOMEMS SENSOR USING EPITAXIAL BIFEO₃ THIN FILM**
Sena Yamamoto¹, Mario Kiuch¹, Takeshi Yoshimura²
¹Sumitomo Precision Products Co., LTD., JAPAN, ²Osaka Metropolitan University, JAPAN
- T20-b** **REDUCING DYNAMIC MEMORY REFRESH OVERHEAD VIA READ-LESS REFRESH OPERATION USING MEMS-BASED MEMORY CELL**
Khanjan M. Joshi, Manu Garg, Mujeeb Yousuf, Pushpapraj Singh
Indian Institute of Technology, Delhi, INDIA



b - Emerging Technologies & New Opportunities for MEMS/NEMS

Internet of Things (IoT) with MEMS/NEMS

- W19-b** **STRETCHABLE DEVICE WITH LOW-ENERGY CONSUMPTION USING POSITIVE PIEZOCONDUCTIVE ELECTRIC COMPONENT**
 Yuji Isano, Shoki Kato, Tamami Takano, Purevdorj Munkhzyaya,
 Nyamjargal Ochirkhuyag, Hiroki Ota
Yokohama National University, JAPAN

b - Emerging Technologies & New Opportunities for MEMS/NEMS

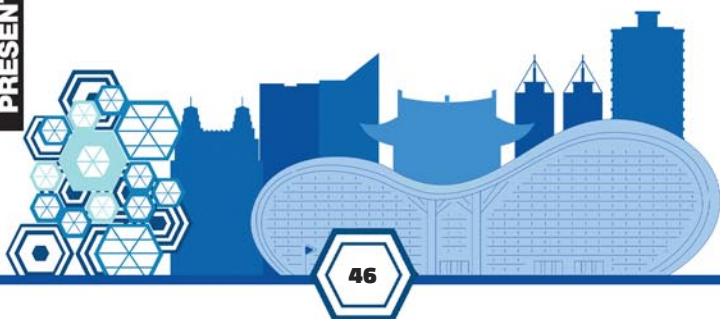
Machine Learning (ML) & Artificial Intelligence (AI)-Enhanced MEMS/NEMS Design, Manufacturing, and Applications

- M21-b** **A MACHINE-LEARNING-ASSISTED SILENT SPEECH INTERFACE UTILIZING MICRO-NEEDLE-ARRAY EMG ELECTRODES AND HIGH-SENSITIVITY STRAIN SENSING ELEMENTS**
 Sheng-Kai Lin¹, Yen-Chun Chen¹, Jing-Han Lin²,
 Pin-Hao Lin¹, Wen-Cheng Kuo², Yao-Joe Yang¹
¹*National Taiwan University, TAIWAN*, ²*National Kaohsiung University of Science and Technology, TAIWAN*
- T21-b** **DEEP REINFORCEMENT LEARNING-BASED PARAMETERS OPTIMIZE PREDICTION MODEL FOR SMOOTH-VERTICAL SIDEWALL PROFILE IN DEEP REACTIVE ION ETCHING PROCESS**
 Fang Wang^{1,2}, Hao Yu^{1,2}, Yechen Miao^{1,2}, Yue He¹,
 Ke Sun¹, Yi Sun¹, Heng Yang^{1,2}, Xinxin Li^{1,2}
¹*Chinese Academy of Sciences (CAS), CHINA*,
²*University of Chinese Academy of Sciences, CHINA*
- W20-b** **ENHANCED REAL-TIME GAS DETECTION ACCURACY BY A SCALABLE MACHINE LEARNING SCHEME**
 Yuan Gao¹, Wei Yue¹, Qiuyang Xiao², Peisheng He¹, Liwei Lin¹
¹*University of California, Berkeley, USA*, ²*Peking University, CHINA*

b - Emerging Technologies & New Opportunities for MEMS/NEMS

MEMS/NEMS for Advancing Scientific Instrumentation and Metrology

- T122-b** **ULTRASONIC PARTICLE LEVITATION USING PIEZOELECTRIC MICROMACHINED ULTRASOUND TRANSDUCER ARRAY FOR NON-CONTACT PARTICLE MANIPULATION**
 Sagnik Ghosh¹, David S. W. Choong¹, Jihang Liu¹,
 Daniel S.-H. Chen¹, Yong Shun Teo¹, Yan Hong¹,
 Alberto Leotti², Domenico Giusti³, Ivan Vezzoli³,
 Yao Zhu¹, Yul Koh¹
¹*Agency for Science, Technology and Research (A*STAR), SINGAPORE*,
²*STMicroelectronics, SINGAPORE*, ³*STMicroelectronics, ITALY*



b - Emerging Technologies & New Opportunities for MEMS/NEMS

Nonlinear Dynamics in MEMS/NEMS

T22-b **ATOMICALLY THIN NEMS FREQUENCY COMB WITH BOTH FREQUENCY TUNABILITY AND RECONFIGURABILITY VIA MECHANICAL MIXING OF TWO EXCITATIONS**
Bo Xu, Zenghui Wang
University of Electronic Science and Technology of China, CHINA

W21-b **NON-HERMITIAN MEMS DISK RESONATOR BASED ON THERMAL-ELASTIC-DAMPING-REGULATION AND DYNAMICAL INTERACTION**
Sen Zhang¹, Lei Yu², Kaixuan He², Ning Zhou², Xin Zhou¹
¹*National University of Defense Technology, CHINA,*
²*East China Institute of Photo-Electronic IC, CHINA*

b - Emerging Technologies & New Opportunities for MEMS/NEMS

Quantum Devices and Systems with MEMS/NEMS

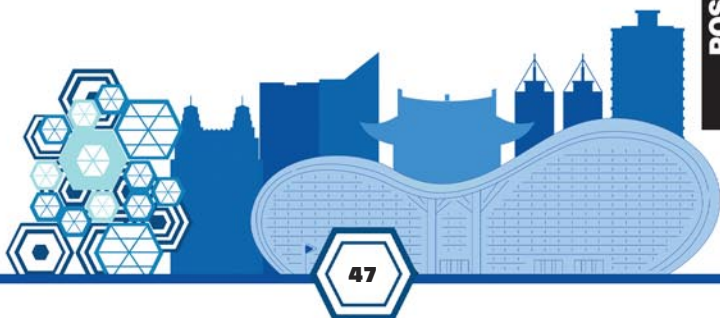
M23-b **ALSCN LAMB WAVE RESONATOR BASED ON NBN SUPERCONDUCTING ELECTRODE AT CRYOGENIC TEMPERATURE**
Wenzhen Li¹, Xuankai Xu¹, Jiawei Li¹, Peng Dong¹, Yiwei Wang¹, Ruihong Xiong¹, Jun Li¹, Tao Wu^{1,2,3,4}
¹*ShanghaiTech University, CHINA,* ²*Chinese Academy of Sciences, CHINA,* ³*University of Chinese Academy of Sciences, CHINA,*
⁴*Shanghai Engineering Research Center of Energy Efficient and Custom AI IC, CHINA*

T23-b **MINIATURE QUANTUM GRADIOMETER USING 3D INTERCONNECTED ATOMIC VAPOR CELLS**
Jianfeng Zhang, Jintang Shang
Southeast University, CHINA

c - Industry MEMS and Advancing MEMS for Products and Sustainability

Measurement Methods for Product Specs

M24-c **WAFER-LEVEL EXTRACTION OF MULTILAYER RESIDUAL STRESS IN PVD-PZT PMUTS THROUGH AN AUTOMATED COUPLED METHOD WITH FEM AND MEASUREMENT**
Prakasha Chigahalli Ramegowda¹, Shyam Trivedi¹, Sagnik Ghosh¹, David Sze Wai Choong¹, Duan Goh Jian¹, Liu Jihang¹, Qian You¹, Domenico Giust², Filippo D'Ercoli², Alberto Leotti³, Yul Koh¹
¹*Agency for Science, Technology and Research (A*STAR), SINGAPORE,*
²*STMicroelectronics, ITALY,* ³*STMicroelectronics, SINGAPORE*



c - Industry MEMS and Advancing MEMS for Products and Sustainability

MEMS Packaging Techniques

- T24-c** **A SANDWICH AU-POROUS TI-DENSE TI MEMS GETTER WITH ON-CHIP SELF-HEATING AND MONITORING FUNCTIONS**
 Haowen Hu³, Chenzhe Du¹, Zhiyu Sun¹, Yufeng Jin^{2,3}, Qiancheng Zhao^{1,2}, Jian Cui^{1,2}
¹Peking University, CHINA, ²National Key Laboratory of Advanced Micro and Nano Manufacture Technology, CHINA, ³Peking University Shenzhen Graduate School, CHINA
- W22-c** **ELECTROSTATIC POLARITY SWITCHING PACKAGING FOR DEGRADATION MITIGATION IN SEAWATER USAGE**
 Steven Tran, Seunbeom Noh, Hanseup Kim
 University of Utah, USA

c - Industry MEMS and Advancing MEMS for Products and Sustainability

MEMS System Design and Integration Approaches

- M25-c** **ALL PRINTED LITHIUM ION BATTERY WITH LIQUID METAL PACKAGE**
 Yuta Ozawa, Daisuke Kuse, Mizuki Funahashi, Kyohei Nagatake, Tamami Takano, Kazuhide Ueno, Hiroki Ota
 Yokohama National University, JAPAN
- T25-c** **DESIGN AND FABRICATION OF A 2-IN-1 MEMS AUDIO TRANSDUCER FOR IN-EAR APPLICATIONS**
 Yu-Chen Chen, Zih-Song Hu, Weileun Fang
 National Tsing Hua University, TAIWAN
- W23-c** **RECONFIGURABLE NON-VOLATILE 4-WAY ROUTING SWITCH WITH ZERO STANDBY POWER**
 Victor Marot, Mukesh K. Kulsreshath, Qi Tang, Manu B. Krishnan, Dinesh Pamunuwa
 University of Bristol, UK

c - Industry MEMS and Advancing MEMS for Products and Sustainability

MEMS/NEMS - CMOS Integration

- M26-c** **A PURE CMOS STACK ELECTROSTATIC MICROMIRROR FEATURING SIMPLIFIED FABRICATION AND STRESS-ADJUSTED MODELING**
 Wenhao Chen¹, Hadi Tavakkoli¹, Bin Zhao², Maojie Zhang², Wibool Piyawattanametha^{3,4}, Yi-Kuen Lee¹
¹Hong Kong University of Science and Technology, HONG KONG, ²CanSemi Technology, Co., Ltd., CHINA, ³King Mongkut's Institute of Technology Ladkrabang, THAILAND, ⁴Michigan State University, USA
- T26-c** **MONOLITHIC ANEMOMETER/THERMOMETER/PRESSURE SENSING CHIP FOR AIR STATIC/DYNAMIC PRESSURE DETECTION**
 Ming-Hsuan Huang, Ting-Fang Wang, Yuanyuan Huang, Mei-Feng Lai, Weileun Fang
 National Tsing Hua University, TAIWAN

MEMS/NEMS - CMOS Integration

- W24-c** **MONOLITHIC INTEGRATED CMOS-MEMS PRESSURE SENSOR WITH PIEZORESISTORS FABRICATED BY COMBINATIONS OF P-TYPE ION IMPLANTATION IN THE STANDARD CMOS PROCESS**
 Fengyang Li, Zhiheng Yu, Changyuan Mai, Jiawei Zhou,
 Shiyang Yuan, Xuanqing Hua, Dacheng Zhang
Peking University, CHINA

d - MEMS & NEMS Materials, Fabrication and Packaging

Advancement in Conventional Materials for MEMS & NEMS

- T27-d** **HIGHLY SENSITIVE CRYOGENIC TEMPERATURE SENSORS UTILIZING CUSTOM-FABRICATED RUTHENIUM OXIDE SLURRY**
 Yonghao Xie, Minmin You, Yanjie Li, Yongpeng Ran,
 Jingquan Liu, Zude Lin
Shanghai Jiao Tong University, CHINA

- W25-d** **HYDROSTATIC STRENGTH AND RESONANT FREQUENCY OF LARGE AND THIN LPCVD SIN DIAPHRAGM WITH ADDED PARYLENE**
 Hongxiang Gao, Junyi Wang, Kunfeng Wang,
 Anik Sengupta, Eun Sok Kim
University of Southern California, USA

- M27-d** **WAFER-SCALE DEMONSTRATION OF A HIGHLY SENSITIVE STRAIN SENSOR BASED ON POLYCRYSTALLINE VO₂**
 Zahra Saadat Somaehsofla¹, Cyrille Masserey¹, Anna Varini¹,
 Denis Flandre², Adrian Mihai Ionescu¹
¹*École Polytechnique Fédérale de Lausanne (EPFL), SWITZERLAND,*
²*Université Catholique de Louvain, BELGIUM*

d - MEMS & NEMS Materials, Fabrication and Packaging

Digital Micromanufacturing

- T28-d** **VIBRATION-BASED AIRFLOW SENSOR WITH THREE-DIMENSIONAL BLUFF BODY STRUCTURE FORMED USING LASER FOLDING TECHNIQUE ON COPPER-POLYIMIDE FILM**
 Kei Ohara, Rihachiro Nakashima, Hidetoshi Takahashi
Keio University, JAPAN

- W26-d** **3D-PRINTED STAINLESS STEEL ELECTRODES FOR ADVANCING MEMS MICROBIAL FUEL CELLS TOWARD SUSTAINABLE ON-CHIP ENERGY**
 Anwar Elhadad, Guangfa Li, Jiaqi Yang, Dehao Liu, Seokheun Choi
State University of New York, Binghamton, USA

d - MEMS & NEMS Materials, Fabrication and Packaging

Generic MEMS & NEMS Manufacturing Techniques

- M28-d** **A METHOD FOR IN-SITU ON-WAFER FOUR-POINT BENDING TEST OF MICROBEAMS**
 Xufeng Wang, Jiakang Li, Yi Chen, Jiawei Zhou,
 Shiyang Yuan, Xuanqing Hua, Dacheng Zhang
Peking University, CHINA

Generic MEMS & NEMS Manufacturing Techniques

- T29-d** **ABNORMAL ORIENTED GRAINS(AOG) CONTROLLED OF $Al_xSc_{1-x}N$ BIMORPH STACK AND PIEZOELECTRIC PROPERTIES CHARACTERIZATION AT 8-INCH WAFER**
 Yucheng Ji^{1,2,3,4}, Anyuan Liu^{1,4}, Ruixiang Yan^{1,4},
 Songsong Zhang^{2,3,4}, Alex Gu¹
¹Shanghai University, CHINA, ²Chengdu Chimesen Technology Co., Ltd., CHINA, ³Shanghai Melon Technology Co. Ltd, CHINA, ⁴Shanghai Industrial μ Technology Research Institute (SITRI), CHINA
- W27-d** **BANDWIDTH AND THERMAL STABILITY ENHANCEMENT OF POLYMER-INTEGRATED PIEZOELECTRIC MICROMACHINED ULTRASONIC TRANSDUCER ARRAY FOR AIR-COUPLED APPLICATIONS**
 Alvaro Rosa, Wolfgang Muehleisen, Annalisa De pastina,
 Javad Abbaszadeh
 Silicon Austria LAB, AUSTRIA
- M29-d** **CREATING DOUBLY RE-ENTRANT STRUCTURES WITH ANY THERMOSETTING POLYMER**
 Qingyang Sun, Tingyi "Leo" Liu
 University of Massachusetts, Amherst, USA
- T30-d** **EXPERIMENTS ON ANISOTROPIC WET ETCH RATE DISTRIBUTION OF GA-FACE GAN CRYSTAL AND LEVEL SET SIMULATION**
 Ye Chen, Xi Chen, Yan Xing, Zaifa Zhou
 Southeast University, CHINA
- W28-d** **RAPID HETEROGENEOUS TRANSPORT USING MICRO/NANO HIERARCHICAL DENDRITIC MESH WICK**
 Xinmeng Zhai^{1,2}, Yan Wang¹, Dongdong Xie^{1,3}, Yuna Sun¹,
 Faheng Zang¹, Zhuoqing Yang¹, Congchun Zhang¹, Guifu Ding¹
¹Shanghai Jiao Tong University, CHINA, ²Harvard University, USA

d - MEMS & NEMS Materials, Fabrication and Packaging

New & Emerging Materials for MEMS/NEMS

- M30-d** **BIODEGRADABLE AND SELF-HEALABLE PIEZOELECTRIC HYDROGEL FOR BIOCOMPATIBLE SOLID-STATE TRANSDUCERS**
 Sujoy Kumar Ghosh, Peisheng He, Fan Xia, Wei Yue,
 Megan Teng, Peggy Tsao, Liwei Lin
 University of California, Berkeley, USA
- T31-d** **FACILE IDENTIFICATION OF CARBON NANOTUBE'S CRYSTAL ORIENTATION USING EPITAXIAL GROWTH OF AUCN NANOWIRES**
 Sunbin Yoon, Joowon Lim, Byeongju Hong, Wonchul Lee
 Hanyang University, KOREA
- W29-d** **HIGHLY SENSITIVE LITHIUM NIOBATE-BASED SAW STRAIN SENSOR WITH ON-CHIP TEMPERATURE COMPENSATION**
 Chunlong Cheng, Jingwen Yang, Xiaoru Li, Tong Tong,
 Huahuang Luo, Zekai Meng, Qingqing Ke
 Sun Yat-sen University, CHINA

New & Emerging Materials for MEMS/NEMS

- M31-d** **IN-SITU SAW/BAW SENSORS BASED ON P(VDF-TrFE) FOR STRAIN AND TEMPERATURE MEASUREMENT**
 Xiaoru Li, Chunlong Cheng, Jingwen Yang, Guoxiang Zhang, Zihan Lu, Xuefei Yan, Huahuang Luo, Zekai Meng, Qingqing Ke
Sun Yat-sen University, CHINA
- T32-d** **INTERACTIVE EFFECTS OF WATER MOLECULES ACROSS A SUSPENDED DOUBLE-LAYER GRAPHENE WITH ELECTRO-MODULATION**
 Yu-Xuan Lu, Wei-Yu Long, Cheng-Yu Lin, Chih-Ting Lin
National Taiwan University, TAIWAN
- W30-d** **NANOSTRUCTURED BORON-DOPED DIAMOND ELECTRODES FOR ENHANCED HEAVY METAL SENSING**
 GM Hasan UI Banna¹, James R. Siegenthaler^{1,2}, Ahmed Azwad Kabir¹, Raul Murillo Martinez¹, Wen Li^{1,2}
¹Michigan State University, USA, ²Fraunhofer USA Center Midwest, USA
- M32-d** **TWISTABLE POLYMER BASED ON RESIDUAL MAGNETIC FLUX VECTOR PROGRAMMING FOR MICRO MIRROR**
 Yangzhi Yu, Yinfeng Xia, Kai Du, Yuanlin Xia, Zhuqing Wang
Sichuan University, CHINA

d - MEMS & NEMS Materials, Fabrication and Packaging

New Fabrication Processes for Making MEMS/NEMS

- T33-d** **A PIONEERING LAYER-BY-LAYER FABRICATION PROCESS FOR HIGH-DENSITY AND HIGH-RESOLUTION DOUBLE-SIDED FLEXIBLE NEURAL ELECTRODES**
 Zixing Li¹, Haoyuan Chen¹, Kejun Tu¹, Jingjing An¹, Kaijie Yang¹, Longchun Wang¹, Jiawei Cao¹, Bin Yang¹, Zhihong Li², Jingquan Liu¹
¹Shanghai Jiao Tong University, CHINA, ²Peking University, CHINA
- W31-d** **FEMTOSECOND LASER INDUCED GRAPHENE BASED ON DOUBLE-LINE METHOD FOR ELECTROMYOGRAPHY ELECTRODE**
 Lingyu Yang, Minmin You, Shuihan Shao, Jingjing An, Bin Yang, Jingquan Liu
Shanghai Jiao Tong University, CHINA
- M33-d** **WAFER-SCALE FERROMAGNETIC SHADOW MASK COMPATIBLE WITH CONTACT ALIGNER FOR DRY ETCHING AND DEPOSITION**
 Taeyeong Kim, Juhee Ko, Jungchul Lee
Korea Advanced Institute of Science and Technology (KAIST), KOREA
- T34-d** **WATER-SOLUBLE AND ENVIRONMENTALLY FRIENDLY UV PHOTODETECTOR FABRICATED THROUGH SOLVENT-FREE MATERIAL PATTERNING**
 Zhiqing Xu, Qinhuo Guo, Lizhou Yang, Jiajun Zhang, Xiwen Liu, Qinghao He, Man Chan, Yunda Wang
Hong Kong University of Science and Technology (HKUST), CHINA

d - MEMS & NEMS Materials, Fabrication and Packaging

Packaging & Assembly

W32-d DEVELOPMENT OF DOUBLE-LAYER-STACKED SILICON INTERPOSER FOR 32X32 MICROMIRROR ARRAY PACKAGING

Biyun Ling¹, Minli Cai^{1,2}, Dalong Chen¹, Xiaoyue Wang¹, Yuwei Han^{1,2}, Yaming Wu^{1,2}

¹Chinese Academy of Sciences (CAS), CHINA,

²University of Chinese Academy of Sciences, CHINA

M34-d EVALUATION OF MEMS GETTER PERFORMANCE BASED ON THE SURFACE ROUGHNESS AND ATOMIC-LEVEL SIMULATION THEREOF

Haowen Hu³, Chenzhe Du¹, Ziyu Sun², Yufeng Jin^{2,3}, Qiancheng Zhao^{1,2}, Jian Cui^{1,2}

¹Peking University, CHINA, ²National Key Laboratory of Advanced Micro and Nano Manufacture Technology, ³Peking University Shenzhen Graduate School, CHINA

T35-d MEMS-IC INTEGRATION STRATEGY BY EMBEDDED SILICON FAN-OUT PACKAGE

Bohan Zhang¹, Lang Chen¹, Chi Zhang^{1,2,3}, Han Xu¹, Wei Wang^{1,2,3}

¹Peking University, CHINA, ²National Key Laboratory of Advanced Micro and Nano Manufacture Technology, CHINA, ³Beijing Advanced Innovation Center for Integrated Circuits, CHINA

e - MEMS Actuators & Power MEMS

Actuator Components & Systems

T36-e A ROBUST ELECTROTHERMAL MICROMIRROR ARRAY BASED ON POLYIMIDE/AL BIMORPHS

Hengzhang Yang^{1,2}, Qiangqiang Liu^{1,2}, Jihui Ni^{1,2}, Wenlong Jiao¹, Xiaodan Mao¹, Yingtao Ding^{1,2}, Anrun Ren^{1,2}, Hui Zhao^{1,2}, Shuailong Zhang^{1,2,3}, Huikai Xie^{1,2}

¹Beijing Institute of Technology, CHINA, ²Ministry of Education of China, CHINA, ³BIT Zhengzhou Research Institute, CHINA

W34-e DEVELOPMENT OF LARGE-RANGE ROTARY INTERFEROMETER USING A GENETIC ALGORITHM FOR MINIATURE FTIR SPECTROMETER

Honglin Qian¹, Huanyu Dai¹, Minjie Zhu¹, Yonggang Jiang², Bing Li¹, Gaopeng Xue¹

¹Harbin Institute of Technology, CHINA, ²Beihang University Technology and Economy Institute, CHINA

M35-e ELECTROSTATIC MEMS SWITCH WITH ISOLATED SWITCHING PATH AND STATE-HOLDING MECHANICAL LATCH STRUCTURES

Yuki Okamoto¹, Ryo Oda^{1,2}, Jun Usami¹, Rihachiro Nakashima^{1,2}, Kei Ohara^{1,2}, Sucheta Gorwadkar¹, Yusuke Takei¹, Hironao Okada¹

¹National Institute of Advanced Industrial Science and Technology (AIST), JAPAN, ²Keio University, JAPAN

Actuator Components & Systems

- T37-e** **HYBRID ACTUATORS WITH TRANSMISSION-SPRING FOR PIEZOELECTRIC MEMS SCANNING MIRROR**
 Hao-Chien Cheng, Weileun Fang
National Tsing Hua University, TAIWAN
- W35-e** **SCAN-ANGLE ENHANCEMENT OF QUASI-STATIC PIEZOELECTRIC MEMS MIRROR BY MULTIPLE RING-SHAPED DESIGN AND CROSS-ELECTRODE ARRANGEMENT**
 Hung-Yu Lin^{1,2}, Hao-Chien Cheng^{1,2}, Mingching Wu²,
 Jerwei Hsieh³, Mei-Feng Lai¹, Weileun Fang¹
¹*National Tsing Hua University, TAIWAN*, ²*Coretronic MEMS Corporation, TAIWAN*, ³*Asia Pacific Microsystems, TAIWAN*
- M36-e** **TEMPERATURE-DEPENDENCE OF STATIC AND DYNAMIC DEFLECTION OF BISTABLE PIEZOELECTRIC MEMS MEMBRANES**
 Philipp Moll, Shareena Muringakodan,
 Ulrich Schmid, Michael Schneider
TU Wien, AUSTRIA

e - MEMS Actuators & Power MEMS

Energy Harvesting Materials, Structures, and Transducers

- T38-e** **A DOUBLE-WELL POTENTIAL EXPANSION MECHANISM FOR OMNI-DIRECTIONAL BROADBAND MEMS BI-STABLE ENERGY HARVESTER**
 Kai Wang¹, Yuan Zhu², Ran Zhang¹, Dengyin Zhang¹
¹*Nanjing University of Posts and Telecommunications, CHINA*,
²*Shanghai Jiao Tong University, CHINA*
- W36-e** **NANOPOROUS SILICON MATERIALS FORMED BY METAL-ASSISTED CHEMICAL ETCHING FOR THERMOELECTRIC GENERATOR**
 Nguyen Van Toan¹, Yijie Li¹, Truong Thi Kim Tuo¹, Khairul Fadzli Samat²,
 Ngyuyen Van Hieu³, Ioana Voiculescu⁴, Takahito Ono¹
¹*Tohoku University, JAPAN*, ²*Universiti Teknikal Malaysia Melaka, MALAYSIA*, ³*Vietnam National University, VIET NAM*,
⁴*Grove School of Engineering, USA*
- T39-e** **SELF-POWERED MOTION AND TACTILE POSITIONING BASED ON A DUAL MODE TRIBOELECTRIC SENSOR WITH CHARGE ACCUMULATING ENCLOSURE FOR SPORTS MONITORING**
 Trilochan Bhatta, Gagan Bahadur Pradhan,
 Shital Sharma, Jae Yeong Park
Kwangwoon University, KOREA
- W37-e** **THERMOELECTRIC GENERATOR WITH THERMAL CONTACT AND COOLING SURFACES USING KIRIGAMI STRUCTURE STOOD UP BY STRETCHING DEFORMATION**
 Atsuki Oguchi, Shingo Terashima, Eiji Iwase
Waseda University, JAPAN

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Manufacturing for Actuators & Power MEMS

- M38-e** **PERFORMANCE ENHANCEMENT IN THERMOELECTRIC GENERATORS USING SELF-CURLING METAL THIN FILMS**
 Milad Shojaeian, Nadezda Kuznetsova, Chen Wang,
 Francisco Molina Lopez, Michael Kraft
KU Leuven, BELGIUM
- T40-e** **SPRING DIAPHRAGM STRUCTURE WITH RING ACTUATOR TO ACHIEVE WIDE BANDWIDTH AND HIGH FIDELITY MICROSPEAKER**
 Chia-Hao Lin¹, Ting-Chou Wei¹, Chin Tseng¹, Tsung-Wen Tsai¹,
 Po-Shen Chen¹, Sung-Cheng Lo², Mei-Feng Lai¹, Weileun Fang^{1,2}
¹*National Tsing Hua University, TAIWAN*, ²*Upbeat Technology, TAIWAN*

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Materials for Actuators & Power MEMS

- W38-e** **CELLULOSE NANOFIBER- BISMUTH TELLURIDE COMPOSITE FILM FOR MICRO THERMOELECTRIC GENERATOR**
 Jianghan Tian¹, Nguyen Van Toan¹, Keita Sakakibara², Takahito Ono¹
¹*Tohoku University, JAPAN*, ²*National Institute of Advanced Industrial Science and Technology (AIST), JAPAN*
- M39-e** **DESIGN OF PIEZOELECTRIC MEMS MICROSPEAKER WITH PARYLENE SPRING FOR PERFORMANCE IMPROVEMENT**
 Zih-Song Hu¹, Chia-Hao Lin¹, Sung-Cheng Lo², Weileun Fang^{1,2}
¹*National Tsing Hua University, TAIWAN*,
²*Upbeat Technology Co., Ltd., TAIWAN*
- T41-e** **HIGH-PERFORMANCE FLEXIBLE MICRO-SUPERCAPACITORS BASED ON NOVEL 2D MBENE AND 3D INTERDIGITATED ELECTRODES**
 Yiwen Ma¹, Wenhe Xia¹, Qingfubo Geng¹, Xinyu Yao¹, Xuan Liu¹,
 Xiaohong Wang², Bingmeng Hu¹
¹*Minzu University of China, CHINA*, ²*Tsinghua University, CHINA*

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Power MEMS Components & Systems

- W39-e** **AN ULTRASONIC WIRELESS POWER TRANSMISSION SYSTEM WITH HIGH CONVERSION EFFICIENCY BASED ON 30% ScAlN PIEZOELECTRIC MEMS TRANSDUCERS**
 Chenyuan Zhang, Zhiwei You, Jiao Xia, Yiwei Guo,
 Junhao Wang, Yipeng Lu
Peking University, CHINA

e - MEMS Actuators & Power MEMS

Self-Powered Devices and Microsystems

- M40-e** **A FLEXIBLE THERMOELECTRIC GENERATOR WITH OPTIMIZED DESIGN FOR LOW-THERMAL HEAT WASTE ENERGY HARVESTING**
 Hao Lv, Yuanlin Xia, Zhuqing Wang
Sichuan University, CHINA
- T42-e** **A TRIBOELECTRIC-POWERED CONTINUOUS WIRELESS COMMUNICATION MICROSYSTEM WITH SYNCHRONOUS ELECTRIC CHARGE EXTRACTION POWER MANAGEMENT**
 Xiangyu Zhao¹, Zerui Xu¹, Yuqi Kang¹, Ziyang Ou¹,
 Yisong Ling¹, Sixing Xu², Xiaohong Wang¹
¹*Tsinghua University, CHINA*, ²*Hunan University, CHINA*
- W40-e** **SELF-POWERED FLEXIBLE MICRO-SUPERCAPACITOR BASED ON OPTIMIZED LASER INDUCED GRAPHENE ELECTRODES FOR SUSTAINABLE ENERGY HARVESTING AND STORAGE**
 Faizan T. Beigh¹, Vishal Singh¹, Bharti Singh², Dhiman Mallick¹
¹*Indian Institute of Technology, Delhi, INDIA*,
²*Delhi Technological University, INDIA*

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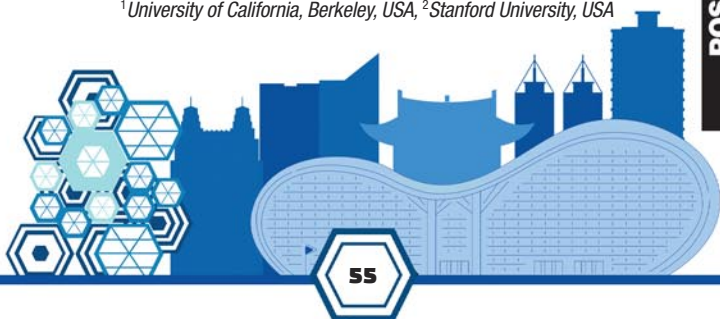
Other Actuators & Power MEMS

- T43-e** **AN ULTRA-LOW TOTAL HARMONIC DISTORTION PIEZOELECTRIC MEMS LOUDSPEAKER WITH DOUBLE-S UNIMORPH ACTUATORS**
 Qincheng Zheng^{1,2}, Ke Cao^{1,2}, Ning Deng^{1,2},
 Chenyu Bai^{1,2}, Yao Lu^{1,2}, Huikai Xie^{1,2}
¹*Beijing Institute of Technology, CHINA*,
²*Ministry of Education of China, CHINA*
- W41-e** **ELECTROSTATIC VIBRATION WITH NO ELECTRICAL SIGNAL DYNAMIC ACTUATION DRIVEN BY THE ELECTRON BEAM**
 Suengyoon Lee, Sunbin Yoon, Byeongju Hong, Won Chui Lee
Hanyang University, KOREA

f - MEMS Physical & Chemical Sensors

Fluidic Sensors

- T44-f** **CONTACTLESS ULTRASONIC FLUID VISCOSITY AND DENSITY MONITORING**
 Pei-Chi (Peggy) Tsao¹, Samantha Averitt², Megan Teng¹,
 Haoyun (Jerry) Tang¹, Ting Chen⁴, Yande Peng¹,
 Wei Yue¹, Liwei Lin¹
¹*University of California, Berkeley, USA*, ²*Stanford University, USA*



Fluidic Sensors

- W42-f** **GAS FLOW SENSING WITH A PIEZORESISTIVE SILICON NANOWIRE-BASED MEMS FORCE SENSOR**
 Levent Demirkazik¹, Umut Kerimzade¹, Masoud Jedari Ghourichaei¹, Onur Aydin¹, Bekir Aksoy¹, Cemal Aydogan², Gokhan Nadar¹, Ivo W. Rangelow^{2,3}, Arda Deniz Yalcinkaya⁴, Halil Bayraktar⁵, Burhanettin Erdem Alaca¹
¹Koç University, TURKEY, ²Ilmenau University of Technology, GERMANY, ³nano analytik GmbH, GERMANY, ⁴Bogazici University, TURKEY, ⁵Istanbul Technical University, TURKEY
- M42-f** **LIQUID VISCOSITY DETECTION BASED ON HARMONIC ENGINEERING AND DUAL-FREQUENCY ULTRASONIC TRANSDUCER ARRAYS**
 Jiao Xia, Aocheng Bao, Junhao Wang, Jinghan Gan, Bowen Sheng, Yipeng Lu
 Peking University, CHINA
- T45-f** **PIEZOELECTRIC ACOUSTIC PRESSURE SENSORS WITH ENHANCED SENSITIVITY AND STIFFNESS BASED ON STRESS CONCENTRATION STRUCTURES AND WEDGE-SHAPE ELECTRODES**
 Zhiwei You, Chong Yang, Lei Zhao, Aocheng Bao, Yipeng Lu
 Peking University, CHINA

f - MEMS Physical & Chemical Sensors
Force & Displacement Sensors

- W43-f** **2-AXIS FORCE PLATE FOR DROPLET COLLISION MEASUREMENT USING LINE SCAN CAMERA AND SAMPLING MOIRÉ METHOD**
 Yukitake Nakahara¹, Satofumi Kato¹, Hiroaki Onoe¹, Choongyeop Lee², YunJung Heo², Hidetoshi Takahashi¹
¹Keio University, JAPAN, ²Kyung Hee University, KOREA
- M43-f** **A NOVEL MULTIPLE MODES RESONANT SENSOR FEATURING BLUE SIDEBAND EXCITATION**
 Jiao Xu¹, Zhuoyue Zheng², Jingqian Xi¹, Ziqian Zhang¹, Huafeng Liu¹, Pan Zhang⁵, Jianlin Chen⁵, Chen Wang³, Michael Kraft³, Yuan Wang², R.P. Martins², Pui-In Mak²
¹Huazhong University of Science and Technology, CHINA, ²University of Macau, CHINA, ³University of Leuven, BELGIUM, ⁴Peking University, CHINA, ⁵Shanghai University, CHINA
- T46-f** **A NOVEL PRESSURE SENSOR WITH COMPOSITE SENSITIVE FILM FOR HIGH PRECISION MEASUREMENT AT BROAD RANGE**
 Xiaopeng Chen¹, Sijia Ling¹, Hanyang Tong¹, Yujing Xiao¹, Jin Zhang², Zhengyin Yu¹, Qinghui Jin¹
¹Ningbo University, CHINA, ²Chinese Academy of Sciences, CHINA

- W44-f** **BIAXIAL GLASS FORCE PLATE USING INCLINED LASER INDUCED BACKSIDE WET ETCHING TROUGH A PRISM**
 Nozomi Ono, Rihachiro Nakashima, Toshihiro Shiratori, Hidetoshi Takahashi
 Keio University, JAPAN

Force & Displacement Sensors

- M44-f** **FLIP-CHIP BONDING OF TACTILE SENSORS WITH STAINLESS STEEL BUMP INTEGRATION FOR SENSING PERFORMANCE IMPROVEMENTS**
Fuchi Shih, Yi-Ming Lai, Mei-Feng Lai, Weileun Fang
National Tsing Hua University, TAIWAN
- T47-f** **FORCE-SENSOR INTEGRATED TOUCH-FEELING SENSOR CAPABLE OF ACQUIRING SUBTLE TEXTURE CHANGES CAUSED BY CONTACT FORCE**
Ryo Akiyama, Nachi Mise, Kyohei Terao, Hidekuni Takao
Kagawa University, JAPAN
- W45-f** **HIGH-FREQUENCY VISION-BASED TACTILE SENSOR WITH EMBEDDED TRANSPARENT PIEZOELECTRIC MODULE FOR HUMANOID ROBOTIC PERCEPTION**
Zhengyi Xie¹, Chunpeng Jiang¹, Haoxiang Jiang^{1,2}, Yimeng Sun³, Bin Yang¹, Jingquan Liu¹
¹Shanghai Jiao Tong University, CHINA, ²Zhangjiang Laboratory, CHINA, ³Shanghai University of Electric Power, CHINA
- M45-f** **HYBRID ORI/KIRIGAMI STRUCTURED PIEZOELECTRIC THIN-FILM SENSORS COVERED BY ELASTOMER WITH HIGHLY DIRECTIONAL STRETCH SENSING ABILITY FOR HEARTBEAT MOTION MONITORING**
Chiranjit Das, Guo-Hua Feng
National Tsing Hua University, TAIWAN
- T48-f** **MICRO FORCE PLATE ARRAY FOR MEASURING 3-AXIS GROUND REACTION FORCES IN ANTS USING SAMPLING MOIRÉ METHOD**
Toshihiro Shiratori, Hidetoshi Takahashi
Keio University, JAPAN
- W46-f** **NANOSTRUCTURE-BASED HIGHLY SENSITIVE AND RELIABLE PIEZO-TRANSMITTANCE STRAIN SENSOR AND INTEGRATED SYSTEM**
Myung-Kun Chung¹, Su-Min Jeon¹, Jae-Soon Yang¹, Jae-Young Yoo², Min-Uk Kim¹, Beom-Jun Kim¹, Tae-Yeon Lee¹, Min-Seung Jo³, Jun-Bo Yoon¹
¹Korea Advanced Institute of Science and Technology (KAIST), KOREA, ²Sungkyunkwan University, KOREA, ³Northwestern University, USA
- M46-f** **PRESSURE SENSITIVE ALUMINUM NITRIDE DRUMHEAD RESONATORS**
Seyyed Mojtaba Hassani Gangaraj¹, Tanya Chauhan¹, Mingyo Park², Azadeh Ansari¹
¹Georgia Institute of Technology, USA, ²Pennsylvania State University, USA
- T49-f** **SINGLE CRYSTAL DIAMOND MEMS FOR REVEALING THE DESORPTION OF ADSORBATES ON O-TERMINATED DIAMOND**
Keyun Gu^{1,2}, Zilong Zhang³, Guo Chen¹, Wen Zhao¹, Guangchao Chen⁴, Jian Huang², Yasuo Koide¹, Satoshi Koizumi¹, Meiyong Liao¹
¹National Institute for Materials Science, JAPAN, ²Shanghai University, CHINA, ³Tohoku University, JAPAN, ⁴University of Chinese Academy of Sciences, CHINA

Force & Displacement Sensors

- W47-f** **STACKED MULBERRY PAPER COATED WITH MXENE FOR HIGHLY SENSITIVE PRESSURE DETECTION WITH WIDE SENSING RANGE**
Sangrim Lee¹, Chaemin Won¹, Jaebeen Ahn¹,
Bowoong Heo², Kyubin Bae², Jongbaeg Kim²,
Taewook Kim¹, Changyong Yim¹, Yunsung Kang¹
¹*Kyungpook National University, KOREA*, ²*Yonsei University, KOREA*
- M47-f** **THREE-DIMENSIONAL HALBACH ARRAY COILS FOR SENSITIVITY ENHANCEMENT OF INDUCTIVE THREE-AXIS FORCE SENSOR**
Yi-Ming Lai, Ruei-Cing Mai, Mei-Feng Lai, Weileun Fang
National Tsing Hua University, TAIWAN

f - MEMS Physical & Chemical Sensors
Gas & Chemical Sensors

- T50-f** **A NOVEL MEMS RESONANT PRESSURE SENSOR OPERATING IN AIR WITH THERMAL ACTUATION PIEZORESISTIVE SENSING**
Chen Wang¹, Appo van der Wiel², Ben Maes²,
Michiel Gidts², Michael Kraft¹
¹*KU Leuven, BELGIUM*, ²*Melexis Company, BELGIUM*
- W48-f** **ACOUSTIC GAS SENSING WITH WEAKLY COUPLED MEMS RESONATORS**
Derin Erkan¹, Ahmet Arif Aslan¹, Erdinc Tatar^{1,2}
¹*Bilkent University, TURKEY*, ²*National Nanotechnology Research Center (UNAM), TURKEY*
- M48-f** **ECO-FRIENDLY FABRICATION OF SUSPENDED 1D NANOHEATERS FOR ULTRALOW POWER TCD-TYPE GAS SENSORS**
Wootaeck Cho, Jihyeon Yoo, Jong-Hyun Kwak, Heungjoo Shin
Ulsan National Institute of Science and Technology, KOREA
- T51-f** **RELIABILITY ENHANCEMENT EXPERIMENTAL STUDY FOR MEMS GAS SENSORS**
Chaoyang Huo¹, Jingxin Wu¹, Minjie Zhu²,
Yuanlin Xia¹, Zhuqing Wang¹
¹*Sichuan University, CHINA*, ²*Instrumentation Technology and Economy Institute, CHINA*
- W49-f** **IONIC-LIQUID GATED ELECTROCHEMICAL CARBON NANOTUBE TRANSISTOR WITH HIGH ON-OFF RATIO FOR SELECTIVE GAS SENSING**
Peisheng He¹, Alex Abelson², Wei Yue¹, Jenny Zhou²,
Liwei Lin¹, Eric Meshot², Steven F. Buchsbaum²
¹*University of California, Berkeley, USA*,
²*Lawrence Livermore National Laboratory, USA*
- M49-f** **ONE-DIMENSIONAL MN-BASED STACKED COORDINATION POLYMER MEMS SENSOR FOR EFFICIENT AMMONIA SENSING**
Jian Wu, Rui Yang, Xue Liu, Aochen Wang, Jingzhu Li, Yuyang Wang,
Nantao Hu, Min Zeng, Jianhua Yang, Zhi Yang
Shanghai Jiao Tong University, CHINA

Gas & Chemical Sensors

- T52-f** **RESONANT CHEMICAL SENSOR PERFORMANCE ENHANCEMENT THROUGH 3D PRINTED SCAFFOLDS**
 Biya D. Haile¹, Nikolas T. Roeske², Hongyu Guo¹,
 Omer T. Inan¹, Luke A. Beardslee²
¹Georgia Institute of Technology, USA,
²Institute for Matter and Systems, USA
- W50-f** **TRANSFER-FREE INTEGRATION OF GRAPHENE ON SUSPENDED MICRO-HOTPLATES FOR NO2 SENSING**
 Leandro N. Sacco, Sten Vollebregt
 Delft University of Technology, NETHERLANDS
- M50-f** **ULTRA-HIGH-SENSITIVITY HYDROGEN NANOGAP MICROSENSOR FOR ENVIRONMENTAL APPLICATIONS BASED ON CHEMICALLY ACTUATED PALLADIUM CANTILEVER BEAMS**
 Amirali Nikeghbal, Rabiul Hasan, Farhan S. Sium,
 Fatemeh Momeni, Adwait Deshpande,
 Seungbeom Noh, Hanseup Kim,
 Carlos H. Mastrangelo
 University of Utah, USA

f - MEMS Physical & Chemical Sensors

Inertial Sensors

- T53-f** **A LINEAR CAPACITIVE GRAVIMETER WITH PSEUDO-DIFFERENTIAL ELECTRODES CAPABLE OF MEASURING EARTH TIDES**
 Mikhail Kanygin¹, Fatemeh Es.haghi¹, Sarai Montanez Munoz¹,
 Douglas Schouten², Glyn Williams-Jones¹, Behraad Bahreyni¹
¹Simon Fraser University, CANADA, ²Ideon Technologies Inc., CANADA
- W51-f** **A NEW SINGLE CHIP HIGH-OVERLOAD TRI-AXIAL MEMS GYROSCOPE WITH MULTI-WHEEL-RING FOR Z-AXIS INPUT RANGE ENHANCEMENT**
 Wenqiang Wei¹, Fang Chen², Huimin Tian¹, Qi Cai¹, Rang Cui¹,
 Xinyu Wang¹, Zhenghao Lu³, Huiliang Cao¹
¹North University of China, CHINA, ²Chinese Academy of Sciences, CHINA, ³Soochow University, CHINA
- M51-f** **A SENSITIVE UNIT COMPENSATION METHOD FOR ENHANCING THE PERFORMANCE OF ELECTROCHEMICAL VIBRATION SENSORS**
 Nan Zhang, Xiaoyu Qi, Zhenchuan Yang, Chengchen Gao
 Peking University, CHINA
- T54-f** **A SINGLE-LOOP NARROW-BAND FORCE REBALANCE CONTROL METHOD WITH TEMPERATURE SELF-COMPENSATION FOR A MEMS GYROSCOPE**
 Chunhua He¹, Yingyu Xu^{1,2}, Heng Wu¹, Qinwen Huang²,
 Qiancheng Zhao^{3,4}, Guizhen Yan^{3,4}
¹Guangdong University of Technology, CHINA, ²Science and Technology on Reliability Physics and Application Technology of Electronic Component Laboratory, CHINA, ³Peking University, CHINA,
⁴National Key Lab of Micro/Nano Fabrication Technology, CHINA

Inertial Sensors

- W52-f** **A WAFER-LEVEL TEST APPROACH FOR ADHESION AND WEAR CHARACTERIZATION IN MEMS ACCELEROMETERS**
 Lukas Ackermann¹, Matthew Lewis¹, Gevorg Aleksanyan¹, Marvin Freier¹, Dominic Palm¹, Jens Anders²
¹Robert Bosch GmbH, GERMANY, ²IIS University of Stuttgart, GERMANY
- M52-f** **CRYSTALLOGRAPHIC ORIENTATION-DEPENDENT THERMAL STABILITY OF TORSION VIBRATION NATURAL FREQUENCY IN SILICON-BASED MEMS RESONATORS**
 Chenzhe Du¹, Zhiyu Sun¹, Chun Xu¹, Zhenchuan Yang^{1,2}, Qiancheng Zhao^{1,2,3}, Jian Cui^{1,2,3}
¹Peking University, CHINA, ²National Key Laboratory of Advanced Micro and Nano Manufacture Technology, CHINA, ³Beijing Advanced Innovation Center for Integrated Circuits, CHINA
- T55-f** **DEMONSTRATION OF $\pm 100\text{G}$ SENSITIVITY BY DROP IMPACT OF HIGH ACCURACY DIFFERENTIAL RESONANT ACCELEROMETER**
 Kei Masunishi, Etsuji Ogawa, Daiki Ono, Fumito Miyazaki, Kengo Uchida, Jumpei Ogawa, Hideaki Murase, Fumitaka Ishibashi, Naoki Hiramatsu, Yasushi Tomizawa
 Toshiba Corporation, JAPAN
- W53-f** **EXPLOITING SHAPED COMBS WITHIN FM ACCELEROMETERS FOR LOW-NOISE AND WIDE DYNAMIC RANGE APPLICATIONS**
 Christian Padovani¹, Luca Pileri¹, Gabriele Gattere², Giacomo Langfelder¹
¹Politecnico di Milano, ITALY, ²STMicroelectronics, ITALY
- M53-f** **IMPROVING THE PERFORMANCE OF MEMS RESONANT SENSORS WITH SYNCHRONIZED PIEZORESISTIVE/CAPACITIVE TRANSDUCTIONS USING SIGNAL FUSION**
 Chengxin Li¹, Fan Wu¹, Chun Zhao², Hemin Zhang³, Mustafa M. Torunbalci⁴, Chen Wang¹, Lieven De Stryker¹, Michael Kraft¹
¹KU Leuven, BELGIUM, ²University of York, UK, ³Northwestern Polytechnical University, CHINA, ⁴Google, USA
- T56-f** **MICROWAVE FREQUENCY COMB INTERROGATION OF HIGH-OVERTONE BULK ACOUSTIC RESONATORS FOR HIGH-SPEED, MULTI-MODAL MASS SENSING**
 Liam G. Connolly^{1,2}, Sean M. Bresler^{1,3}, David A. Long¹, Jason J. Gorman¹
¹National Institute of Standards and Technology (NIST), USA, ²Johns Hopkins University, USA, ³University of Maryland, USA
- W54-f** **PHASE COMPENSATION METHOD FOR THE DRIVE LOOP OF MEMS GYROSCOPE BASED ON DUAL PHASE-LOCKED LOOP SYNCHRONOUS TRACKING**
 Chun Xu¹, Qiancheng Zhao^{1,2,3}, Jian Cui^{1,2,3}
¹Peking University, CHINA, ²National Key Laboratory of Advanced Micro and Nano Manufacture Technology, CHINA, ³Beijing Advanced Innovation Center for Integrated Circuits, CHINA

Inertial Sensors

- M54-f** **ULTRA-SENSITIVE, HIGH BANDWIDTH PHOTONIC-MEMS SEISMIC SENSOR**
 Farnaz Ebrahimi Argi^{1,2}, Ayman Manzoor¹, Hamed Sattari¹, Yves Petremand¹, Dara Bayat¹, Luigi Ferraioli², Antoniou Anastasios², Domenico Giardini², Katrin Plenkers³, Arno Hoogerwerf¹, Homa Zarebidaki¹, Guido Spinola Durante¹, Amir H. Ghadimi¹, Linus Villiger², Stefan Wiemer², Michel Despont¹
¹CSEM, SWITZERLAND, ²ETH Zürich, SWITZERLAND, ³GMuG, GERMANY

f - MEMS Physical & Chemical Sensors

Manufacturing Techniques for Physical Sensors

- T57-f** **HIGHLY SENSITIVE PRESSURE SENSOR FABRICATED BY COATING MXene TO SURFACE-TREATED ECO-FLEX FOR RELIABLE NETWORK**
 Dokyung Kim^{1,2}, Jaesam Sim¹, Dong-Weon Lee²
¹Korea Institute of Industrial Technology, KOREA, ²Chonnam National University, KOREA
- W55-f** **INKJET-PRINTED MN-CO-NI-O CERAMIC MICROBEADS TOWARDS HIGH-SENSITIVITY AND HIGH-STABILITY TEMPERATURE SENSING AT ROOM TEMPERATURE**
 Yongpeng Ran, Yanjie Li, Xiuyan Li, Zude Lin, Bin Yang, Jingquan Liu, Minmin You
 Shanghai Jiao Tong University, CHINA

f - MEMS Physical & Chemical Sensors

Materials for Physical Sensors

- M55-f** **DIAMOND MEMS MAGNETIC FORCE SENSOR TOWARD FEMTONEWTON AT ROOM TEMPERATURE**
 Zilong Zhang¹, Zhijian Zhao¹, Meiyong Liao², Takahito Ono¹, Masaya Toda¹
¹Tohoku University, JAPAN, ²National Institute for Materials Science, JAPAN

f - MEMS Physical & Chemical Sensors

Metrology and Measurement Techniques for MEMS/NEMS Sensors

- T58-f** **IDENTIFICATION OF STRUCTURE IMBALANCE FOR MEMS TUNING-FORK RESONATORS BASED ON MULTI TRANSFER FUNCTIONS SYNTHESIS**
 Jian Cui^{1,2,3}, Chenzhe Du², Yi Tang², Qiancheng Zhao^{1,2,3}
¹National Key Laboratory of Advanced Micro and Nano Manufacture Technology, CHINA, ²Peking University, CHINA, ³Beijing Advanced Innovation Center for Integrated Circuits, CHINA
- W56-f** **OPTICAL CANTILEVER USING DIFFRACTION GRATING AND SAMPLING MOIRÉ METHOD**
 Soya Sato¹, Toshihiro Shiratori¹, Tetsuo Kan², Hidetoshi Takahashi¹
¹Keio University, JAPAN, ²University of Electro-Communications, JAPAN

Metrology and Measurement Techniques for MEMS/NEMS Sensors

- M56-f** **SENSITIVITY-ENHANCED SURFACE ACOUSTIC WAVE HUMIDITY SENSOR BASED ON A NONLINEAR PARITY TIME SYMMETRIC SYSTEM BIASED AT THE EXCEPTIONAL POINT**
 Zhenyu Wei, Jianqiu Huang, Qing-an Huang
Southeast University, CHINA

f - MEMS Physical & Chemical Sensors

Nanoscale Physical Sensors

- T59-f** **GHOST TOUCH FREE WIRELESS NANOGAP CAPACITIVE PRESSURE SENSOR**
 Jae-Soon Yang¹, Myung-Kun Chung¹, Jae-Young Yoo²,
 Beom-Jun Kim¹, Sung-Ho Kim¹, Se-Yoon Jung¹,
 Tae-Yeon Lee¹, Min-Uk Kim¹, Jun-Bo Yoon¹
¹*Korea Advanced Institute of Science and Technology (KAIST), KOREA*,
²*Sungkyunkwan University, KOREA*

f - MEMS Physical & Chemical Sensors

Sonic & Ultrasonic MEMS Transducers

- W57-f** **A CMOS-MEMS ULTRASONIC TRANSCIEVER WITH BIPOLAR-BIASED DIFFERENTIAL CMUT TRANSDUCERS**
 Yu-Cheng Lin, Tzu-Yun Huang, Ming-Huang Li
National Tsing Hua University, TAIWAN
- M57-f** **ACOUSTICALLY DRIVEN SCANNING MIRROR ENHANCED BY HELMHOLTZ RESONATOR UNIT**
 Masahiro Fukuta¹, Rihachiro Nakashima¹,
 Tetsuo Kan², Hidetoshi Takahashi¹
¹*Keio University, JAPAN*, ²*University of Electro-Communications, JAPAN*
- T60-f** **AN ELECTROCHEMICAL VELOCITY-TYPE VECTOR HYDROPHONE FOR DIRECT DETECTION OF UNDERWATER ACOUSTIC PARTICLE VELOCITY**
 Nan Zhang, Xiaoyu Qi, Zhenchuan Yang, Chengchen Gao
Peking University, CHINA
- W58-f** **AN IN-DEPTH ACOUSTIC CHARACTERIZATION MAP AT THE WAFER LEVEL UTILIZING ADVANCED OPTICAL MICROPHONE**
 Luigi Barretta¹, Rossana Scaldaferrri¹, Alessandro S. Savoia²,
 Carlo L. Prelini¹, Carla M. Lazzari¹, Yul Koh³, Sagnik Ghosh³,
 Daniel S-H. Chen³, Andrea Di Matteo¹, Marco Ferrera¹,
 Domenico Giusti¹
¹*STMicroelectronics, ITALY*, ²*Roma Tre University, ITALY*, ³*Agency for Science, Technology and Research (A*STAR), SINGAPORE*
- M58-f** **BIOLOGICAL BONE AGE ASSESSMENT VIA PMUTS**
 Nikita G. Lukhanin, Fan Xia, Sean R. Isomatsu, Megan Teng, Liwei Lin
University of California, Berkeley, USA

Sonic & Ultrasonic MEMS Transducers

- T61-f DYNAMIC PMUTS PACKAGING USING SHAPE MEMORY ALLOY**
 Megan Teng, Peggy Tsao, Wei Yue, Fan Xia,
 Peisheng He, Yande Peng, Liwei Lin
University of California, Berkeley, USA
- W59-f FABRICATION OF WAFER-BONDED 2D CMUT ARRAY WITH GLASS-FILLED TRENCHES**
 Chaerin Oh¹, Seyoung Park¹, Jongcheol Park²,
 Joontaek Jung², Hyunjoo J. Lee¹
¹*Korea Advanced Institute of Science and Technology (KAIST), KOREA* and ²*National NanoFab Center, KOREA*
- M59-f MONOLITHIC INTEGRATION OF ACOUSTIC ENRICHMENT AND RESONANT SENSING FOR TRACE DETECTION OF MICRO-PLASTICS**
 Yue Wang¹, Wenqi Fan¹, Liang Huang¹, Jingui Qian^{1,2}
¹*Hefei University of Technology, CHINA*, ²*Southeast University, CHINA*
- T62-f NONINVASIVE ARTERIAL MOTION MONITORING WITH ALUMINUM NITRIDE-BASED PIEZOELECTRIC MICROMACHINED ULTRASONIC TRANSDUCER**
 Yunhao Wang^{1,2,3}, Junxiang Cai^{1,2,3}, Tao Wu^{1,2,3}, Xinxin Li^{1,2,3}
¹*Chinese Academy of Sciences (CAS), CHINA*, ²*ShanghaiTech University, CHINA*, ³*University of Chinese Academy of Sciences, CHINA*
- W60-f PLANETARY GEAR FAULT DETECTION USING PMUT BASED ACOUSTIC EMISSION SENSOR**
 Hanjie Dou, Tao Liu, Xiao Yang, Zhihao Li, Jixuan Zhang,
 Jiaqian Yang, Yuchen Mao, Xiaojing Mu
Chongqing University, CHINA
- M60-f REAL-TIME DIFFERENTIAL ULTRASONIC FLOW SENSING ENABLED BY PMUT PHASED ARRAY WITH A NOVEL V-SHAPED BEAM PATTERN**
 Yufeng Gao, Xili Wang, Lei Zhao, Yipeng Lu
Peking University, CHINA
- T63-f STRAIN-INSENSITIVE, STRETCHABLE THERMOACOUSTIC LOUDSPEAKER WITH ENTANGLED CARBON NANOTUBES**
 Sangjun Sim¹, Eunhwan Jo², Hyungyu Im¹, Kyubin Bae¹,
 Yunsung Kang³, Jongbaeg Kim¹
¹*Yonsei University, KOREA*, ²*Kumoh National Institute of Technology, KOREA*, ³*Kyungpook National University, KOREA*

f - MEMS Physical & Chemical Sensors

Other Physical Sensors

- W61-f A HIGH EFFICIENCY MINIATURE MULTI-TIP CORONA CHARGER FOR NANOPARTICLE SENSORS**
 Chandrashekhar Choudhary, Tao Li
University of Cincinnati, USA

Other Physical Sensors

M61-f A HIGH SENSITIVITY SANDWICH-TYPE TERAHERTZ METASURFACE MICROFLUIDIC SENSOR FOR DIRECTLY DETECTION OF AQUEOUS SOLUTIONS

Yunhao Cao¹, Hongshun Sun¹, Yusa Chen¹, Lijun Ma¹, Liye Li¹, Shixiong Liang², Shengxiao Jin³, Wengang Wu¹

¹Peking University, CHINA, ²Tianjin University, CHINA, ³National Key Laboratory of Science and Technology on Space Microwave, CHINA

T64-f SELF-ADAPTIVE 2-DOF HYBRID WEAKLY COUPLED SYSTEM WITH MEMS BAW RESONATORS

Bernardo P. Madeira¹, Ruopeng Chen¹, Linlin Wang¹, Chen Wang¹, Fadwa El Jaouhari², Yuan Wang³, Javier Collado¹, Chun Zhao⁴, Georges Gielen¹, Michael Kraft¹

¹KU Leuven, BELGIUM, ²University of Montpellier, FRANCE,

³University of Macau, CHINA, ⁴University of York, UK

W62-f HIGH-PERFORMANCE MEMS MAGNETIC SENSOR BASED ON A SMART TUNABLE RESONATOR

Hanin Amara, Nadeem Tariq Beigh, Nouha Alcheikh
Khalifa University, UAE

M62-f MICROELECTROMECHANICAL 2-BIT LOGIC DEVICE VIA FREQUENCY COMB GENERATION

Hongyu Chen^{1,2}, Dongyang Chen¹, Chen Wang², Ronghua Huan¹, Michael Kraft², Jin Xie¹

¹Zhejiang University, CHINA, ²KU Leuven, BELGIUM

T65-f MULTI-DEGREE OF FREEDOM AND LARGE SCAN RANGE ELECTROTHERMAL MICROMIRROR INTEGRATED WITH THERMAL CONVECTION-BASED MIRROR PLATE POSITION SENSORS

Anrun Ren^{1,2}, Yingtao Ding^{1,2}, Hengzhang Yang^{1,2}, Ziyue Zhang^{1,2}, Hui Zhao^{1,2}, Huikai Xie^{1,2}

¹Beijing Institute of Technology, CHINA,

²Ministry of Education of China, CHINA

W63-f SURFACE INSPECTION OF LIQUID AND ICE LAYERS USING A WIDE-BANDWIDTH AND HIGHLY DIRECTIONAL ULTRASONIC TRANSDUCER

Junhao Wang, Jiao Xia, Aocheng Bao, Chong Yang, Ting Xie, Jinghan Gan, Lei Zhao, Wei Wang, Yipeng Lu

Peking University, CHINA

g - MEMS/NEMS for Optical, RF and Electromagnetics

Electrical Field and Magnetic Field Sensors and Transducers

T66-g A CONTACTLESS DC CURRENT SENSOR BASED ON THIN-FILM LITHIUM NIOBATE SO-MODE LAMB WAVE RESONATOR

Wenwei Gao¹, Hanlun Guan¹, Chenyao Zhu², Huikai Xie^{1,3}, Feng Gao⁴, Xiaoyi Wang^{1,3}

¹Beijing Institute of Technology, CHINA, ²Baotou INST Magnetic

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Micrelectronic and Micrsystem, CHINA, ⁴ZJU-Hangzhou Global

Scientific and Technological Innovation Center, CHINA

g - MEMS/NEMS for Optical, RF and Electromagnetics

Free Space Optical Components & Systems

- W64-g MERGING MEMS VAPOR CELLS WITH METASURFACES FOR NEXT-GEN CHIP-SCALE ATOMIC CLOCKS**
 Ponrapee Prutphongs¹, Yuto Kataoka¹,
 Motoaki Hara², Kentaro Iwami¹
¹Tokyo University of Agriculture and Technology, JAPAN, ²National
 Institute of Information and Communications Technology, JAPAN
- M63-g MICROFABRICATED ROBOT HAND SYSTEM INTEGRATED WITH TRANSPARENT SUCTIONING HEAD AND DUAL-METALENS CAMERA**
 Atsushi Hasegawa¹, Keisuke Ozawa², Yuki Abe², Koichiro Matsumoto²,
 Mineki Taoka², Takeshi Yamagishi², Kentaro Iwami¹
¹Tokyo University of Agriculture and Technology, JAPAN,
²Samsung R&D Institute Japan, JAPAN
- T67-g POLARIZATION-INDEPENDENT WAVELENGTH-MULTIPLEXED FULL-COLOR METASURFACE HOLOGRAM BASED ON HIGH-ASPECT-RATIO SILICON NITRIDE NANOPILLARS**
 Masakazu Yamaguchi, Tetsuhito Omori, Mitsutoshi Hada,
 Junpei Beppu, Kentaro Iwami
 Tokyo University of Agriculture and Technology, JAPAN
- W65-g SIGNIFICANTLY ENHANCED BANDWIDTH OF A DUAL-AXIS PIEZOELECTRIC QUASI-STATIC MEMS MIRROR FOR MINIATURIZED LASER TRACKING**
 Anna Li^{1,2}, Hao Huang^{1,2}, Yongquan Su^{1,3}, Cheng Zhang^{1,2},
 Jiachang Zhang^{1,2}, Yonggui Zhang¹, Lihao Wang^{1,4},
 Yichen Liu^{1,3}, Yang Wang^{1,2}, Zhenyu Wu^{1,2,3,4,5}
¹Shanghai Institute of Microsystem and Information Technology,
 CHINA, ²University of Chinese Academy of Sciences, CHINA,
³Shanghai Industrial μ Technology Research Institute, CHINA,
⁴Shanghai MExpert Technologies Co., Ltd, CHINA,
⁵Shanghai University, CHINA

g - MEMS/NEMS for Optical, RF and Electromagnetics

Infrared (IR) Sensors and Imaging Systems

- M64-g CMOS MICROMACHINED CAPACITIVE SENSORS FOR UNCOOLED INFRARED DETECTION**
 Yan-Cheng Liu, Michael S.-C. Lu
 National Tsing Hua University, TAIWAN
- T68-g FABRICATION OF FLEXIBLE NEAR-INFRARED-TO-VISIBLE LIGHT UPCONVERSION DEVICE ENHANCED BY 3D PRINTED MICROLENS ARRAY FOR LOW-COST NEAR-INFRARED IMAGING SENSORS**
 Nankun Zhang¹, Po-Han Huang^{1,2}, Jerker Widengren¹,
 Haichun Liu¹, Frank Niklaus¹
¹KTH Royal Institute of Technology, SWEDEN,
²NTHU National Tsing Hua University, TAIWAN

Infrared (IR) Sensors and Imaging Systems

W66-g NARROW ELECTRODE SPACING FOR ENHANCED SENSITIVITY OF P-TSI/P-SI NANOHOLE-ARRAY MID-IR PHOTODETECTOR

Elyas A. Ashenafi¹, Daiji Noda², Ryo Ohta², Tetsuo Kan¹

¹University of Electro-Communications, JAPAN,

²Micromachine Center, JAPAN

M65-g PLASMONICALLY ENHANCED ALSCN NANOPATES AS UNCOOLED AND ULTRA-FAST SINGLE-PIXEL DETECTORS FOR IR IMAGING

Aurelio Venditti, Enise F. Altin, Walter Gubinelli, Farah Ben Ayed,

Luca Colombo, Pietro Simeoni, Ben Davaji, Matteo Rinaldi

Northeastern University, USA

g - MEMS/NEMS for Optical, RF and Electromagnetics

Manufacturing for Electromagnetic Transducers

T69-g MINIATURIZED ELECTROMAGNETIC ACTUATOR FOR TACTILE DISPLAY DEVICES WITH HIGH SPATIAL RESOLUTION

Hussein S. Musa, Shamin Sadrafshari, Uriel Martinez-Hernandez,

Ali Mohammadi

University of Bath, UK

g - MEMS/NEMS for Optical, RF and Electromagnetics

MEMS for Timing & Frequency Control

W67-g GEOMETRICALLY MODIFIED SILICON RESONATORS WITH SUB-PPM LINEAR TEMPERATURE COEFFICIENT OF FREQUENCY

Ashudeep¹, Azadeh Jafari¹, Abid Ali¹, Amirmohammad Zare¹,

Siddharth Kumanduri², Anosh Daruwalla², Behraad Bahreyni¹

¹Simon Fraser University, CANADA, ²Stathera, Inc., CANADA

M66-g HIGH-PERFORMANCE PIEZOELECTRIC MEMS RESONATORS AND OSCILLATORS LEVERAGING ADVANCED HIGH-ORDER SUPPORT TRANSDUCER TOPOLOGIES

You-Ting Lin, Chin-Yu Chang, Sheng-Shian Li

National Tsing Hua University, TAIWAN

T70-g INNOVATING ST-CUT QUARTZ WITH MEMS: HIGH Q SMALL RESONATORS WITH HIGH OVEN GAIN AND LOW POWER OVENIZATION

Bokyung Suh, Xinyi Fang, Gianluca Piazza

Carnegie Mellon University, USA

g - MEMS/NEMS for Optical, RF and Electromagnetics

Photonic Components & Systems

W68-g A TIP-TILT-PISTON PIEZOELECTRIC MICROMIRROR WITH A DOUBLE-S SHAPED UNIMORPH SPUTTERED PZT STRUCTURE

Ke Cao^{1,2}, Qincheng Zheng^{1,2}, Bo Xie^{1,2}, Ning Deng^{1,2},

Hui Shang^{1,2}, Hui Zhao^{1,2}, Yao Lu^{1,2}, Huikai Xie^{1,2}

¹Beijing Institute of Technology, CHINA,

²Ministry of Education of China, CHINA

Photonic Components & Systems

- M67-g** **ASYMMETRICAL MEMS MIRROR FOR COMPACT-SIZE AND WIDE FIELD-OF-VIEW AR DISPLAY EQUIPMENT**
 Yusuke Sakata, Masaya Nakazumi, Kensuke Mihara
Panasonic Industry Co., Ltd, JAPAN
- T71-g** **CHARACTERIZATION OF ULTRA-SENSITIVE NEMS PHOTONIC MODULATORS – OVERCOMING PRECISION MEASUREMENT CHALLENGES**
 Andrew Cochran, Harshvardhan Gupta, Maysamreza Chamanzar, Gianluca Piazza
Carnegie Mellon University, USA
- W69-g** **DEVELOPMENT OF THE MULTIPOINT FOCUSING METASURFACE FOR LASER-INDUCED BREAKDOWN SPECTROSCOPY**
 Satoshi Ikezawa¹, Kentaro Iwami², Eiji Iwase¹
¹Waseda University, JAPAN, ²Tokyo University of Agriculture and Technology, JAPAN
- M68-g** **EFFICIENT MID-INFRARED ACOUSTO-OPTIC MODULATION IN SILICON PHOTONIC DEVICES USING LITHIUM NIOBATE**
 Siyu Xu¹, Weixin Liu¹, Chengkuo Lee^{1,2}
¹National University of Singapore, SINGAPORE, ²National Centre for Advanced Integrated Photonics, SINGAPORE
- T72-g** **PLASMON-ENHANCED GRAPHENE PHOTOTHERMOELECTRIC DETECTOR FOR MID-INFRARED SENSING APPLICATIONS**
 Pen-Sheng Lin¹, Shayan Parhizkar^{2,3}, Arne Quellmalz¹, Nour Negm^{2,3}, Stephan Suckow³, Aron Cummings⁴, Alba Centeno⁵, Amaia Zurutuza⁵, Max Lemme^{2,3}, Frank Niklaus¹, Kristinn Gylfason¹
¹KTH Royal Institute of Technology, SWEDEN, ²RWTH Aachen University, GERMANY, ³AMO GmbH, GERMANY, ⁴Catalan Institute of Nanoscience and Nanotechnology, SPAIN, ⁵Graphenea S.A., SPAIN
- W70-g** **SUB-MICRON-THICK SI MEMBRANE SURFACE PLASMON COUPLING STRUCTURE FOR REDUCING UNWANTED PROPAGATION MODES INSIDE SI**
 Tetsuya Ozawa, Abubakr Eslam, Tetsuo Kan
University of Electro-Communications, JAPAN

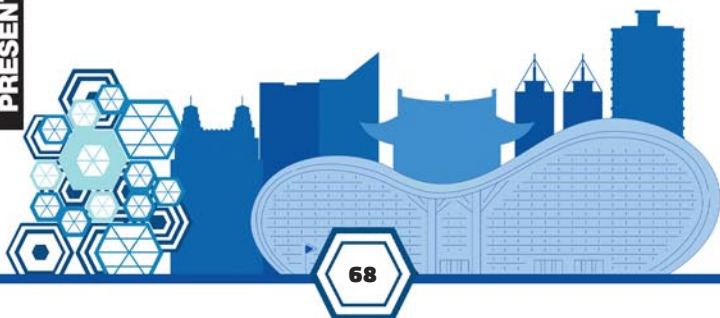
g - MEMS/NEMS for Optical, RF and Electromagnetics

RF MEMS Components & Systems

- M69-g** **3.5 GHZ THERMO-ACOUSTIC PHASE MODULATOR BASED ON Z-CUT LINBO3 THIN FILM**
 Xuankai Xu¹, Yushuai Liu¹, Ruihong Xiong¹, Tao Wu^{1,2}
¹ShanghaiTech University, CHINA, ²Chinese Academy of Sciences, CHINA, ³Shanghai Engineering Research Center of Energy Efficient and Custom AI IC, CHINA
- T73-g** **6 GHZ LITHIUM NIOBATE ON INSULATOR LOW-LOSS SAW DELAY LINE ADAPTING NON-LEAKY COMPOSITE WAVEGUIDE MODE**
 Zhi-Qiang Lee¹, Sung-Yuan Huang¹, Tzu-Hsuan Hsu^{1,2}, Joshua Campbell², Jack Kramer², Ruo Chen Lu², Ming-Huang Li¹
¹National Tsing Hua University, TAIWAN, ²University of Texas, Austin, USA

RF MEMS Components & Systems

- W71-g** **A 4.3 GHZ LITHIUM NIOBATE ON INSULATOR WIDEBAND SURFACE ACOUSTIC WAVE DELAY LINE WITH MULTI-MODE COMPOSITION**
 Sung-Yuan Huang¹, Zhi-Qiang Lee¹, Tzu-Hsuan Hsu^{1,2}, Joshua Campbell², Jack Kramer², Ruo Chen Lu², Ming-Huang Li¹
¹National Tsing Hua University, TAIWAN, ²University of Texas, Austin, USA
- M70-g** **A KU-BAND ACOUSTIC FILTER WITH IL OF 2.0 DB AND FBW OF 13.1% BASED ON Z-CUT LITHIUM NIOBATE THIN FILM**
 Fuhong Lin¹, Yiming Wang¹, Kai Yang¹, Jiming Fang¹, Jie Chen¹, Meijuan Li¹, Chengjie Zuo^{1,2,3}
¹University of Science and Technology of China, CHINA, ²YUNTA Technologies, CHINA, ³ANUKI Technologies, CHINA
- T74-g** **DESIGN AND IMPLEMENTATION OF A GUIDED SURFACE ACOUSTIC WAVE DIRECTIONAL COUPLER FOR PHONONIC INTEGRATED CIRCUITS**
 Jack Guida, Siddhartha Ghosh
 Northeastern University, USA
- W72-g** **DOUBLE-SIDED HEAT DISSIPATION FOR ACOUSTIC RESONATORS BASED ON LITHIUM NIOBATE ON SAPPHIRE**
 Fangsheng Qian, Zijun Ren, Wei Wei, Jiashuai Xu, Junyan Zheng, Xingyu Liu, Yansong Yang
 Hong Kong University of Science and Technology (HKUST), HONG KONG
- M71-g** **EXPERIMENTAL STUDY OF Q-BOOSTING IN TPOS RESONATORS USING CONVENTIONAL AND COUPLED RESONATOR ARCHITECTURE**
 Raeann Jesma R¹, Ken-Wei Tang², Sheng-Shian Li², Gayathri Pillai¹
¹Indian Institute of Science, INDIA, ²National Tsing Hua University, TAIWAN
- T75-g** **SOLIDLY MOUNTED LONGITUDINALLY EXCITED A1 MODE RESONATOR BASED ON THE LINBO₃/Metal/SiO₂/SiC**
 Xiaoli Fang^{1,2}, Jinbo Wu³, Shibin Zhang^{1,2}, Pengcheng Zheng¹, Xinjian Ke^{1,2}, Juxing He^{1,2}, Mijing Sun¹, Xin Ou^{1,2}
¹Chinese Academy of Sciences (CAS), CHINA, ²University of Chinese Academy of Sciences, CHINA, ³Shanghai Xin Ou Integration Technology Company Ltd, CHINA
- W73-g** **SEALED CAVITY BULK ACOUSTIC WAVE RESONATOR WITH COUPLING AND TCF ENHANCEMENT**
 Jiashuai Xu, Zijun Ren, Yansong Yang
 Hong Kong University of Science and Technology (HKUST), HONG KONG



g - MEMS/NEMS for Optical, RF and Electromagnetics

THz MEMS Components & Systems

- M72-g ANGLE-MULTIPLEXED TERAHERTZ FREQUENCY-SELECTIVE FINGERPRINT SENSOR: BROADBAND IDENTIFICATION OF CHIRAL ENANTIOMERS**
 Hongshun Sun¹, Yunhao Cao¹, Yusa Chen¹, Liye Li¹, Lijun Ma¹, Shengxiao Jin², Guodong Gu³, Zhihong Feng³, Wengang Wu¹
¹*Peking University, CHINA*, ²*National Key Laboratory of Science and Technology on Space Microwave, CHINA*, ³*National Key Laboratory of Solid-State Microwave Devices and Circuits, CHINA*

g - MEMS/NEMS for Optical, RF and Electromagnetics

Other Electromagnetic MEMS/NEMS

- T76-g MULTI-DOF DYNAMIC MODELING OF FREQUENCY DRIFT AND PACKAGE OPTIMIZATION GUIDELINE FOR 2D MICROMIRRORS**
 Ze-Yu Zhou, Kai-Ming Hu, Er-Qi Tu, Xiao-Yong Fang
Shanghai Jiao Tong University, CHINA

h - Micro- & Nanofluidics

Biological and Medical Microfluidics and Nanofluidics

- M73-h DRILLING BACTERIAL MOTILITY IN CONFINED SPACES INVESTIGATED USING SUB-MICRON WIDTH FLUIDIC CHANNELS**
 Yoshiki Shimada, Aoba Yoshioka, Naoki Uemura, Daisuke Nakane, Tetsuo Kan
University of Electro-Communications, JAPAN
- T77-h IN VITRO STUDY OF LUNG CONNECTIVE TISSUE STIFFNESS AT VARIOUS OXYGEN TENSIONS AND GRADIENTS**
 Heng-Hua Hsu¹, Ping-Liang Ko^{1,2}, Dao-Ming Chang¹, Yi-Chung Tung¹
¹*Academia Sinica, TAIWAN*, ²*National Taiwan University, TAIWAN*
- W74-h LOW-COST, HIGH-PERFORMANCE DIGITAL MICROFLUIDIC CHIPS FOR REAL-TIME PCR USING REWORKABLE SUBSTRATES**
 Zhaoduo Tong^{1,2}, Chuanjie Shen^{1,2}, Xin Xu¹, Weidong Yang^{1,2}, Yan Li³, Fangliang Xu^{1,2}, Zhenhua Wu^{1,2}, Lin Zhou^{1,2}, Hongju Mao^{1,2}
¹*Chinese Academy of Sciences (CAS), CHINA*, ²*University of Chinese Academy of Sciences, CHINA*, ³*Fudan University, CHINA*
- M74-h MICROFLUIDIC PLATFORM FOR HIGH-RESOLUTION IMAGING OF OOMYCETE SPORES EXPOSED TO OSMOTIC STRESS**
 Yiling Sun, Ayelen Tayagui, Ashley Garrill, Volker Nock
University of Canterbury, NEW ZEALAND
- T78-h SIMULTANEOUS ANALYSIS OF ALZHEIMER'S DISEASE BIOMARKERS USING CASCADED MICROFLUIDIC CAPTURE ARRAYS**
 Pengcheng Zhao^{1,2}, Jieyu Wang^{1,2}, Jiangyu Ji^{1,2}, Huiying Liu², Guowu Ma², Hongju Mao^{1,3}, Jianan Hui^{1,3}
¹*Chinese Academy of Sciences (CAS), CHINA*, ²*Dalian Medical University, CHINA*, ³*University of Chinese Academy of Sciences, CHINA*

h - Micro- & Nanofluidics

Generic Microfluidics & Nanofluidics

- W75-h HIGH-THROUGHPUT ACOUSTIC SORTING OF CELLULAR-SIZED MICROPARTICLES IN 3D MICROFLUIDIC CHANNELS**
 Akash Roy, Baptiste Neff, Kianoush Sadeghian Esfahani,
 Anik Sengupta, Eun S. Kim
University of Southern California, USA

h - Micro- & Nanofluidics

**Integrated/Embedded Microfluidics and
Nanofluidic Systems & Platforms**

- M75-h GUT-ON-A-CHIP REVEALS REDUCED NANOPLASTIC-INDUCED INFLAMMATION THROUGH ENHANCED PERISTALSIS**
 Junlei Han^{1,2}, Huimin Li^{1,2}, Zhipeng Xu³, Jun Chen¹,
 Chaoyang Shi², Li Wang¹
¹*Qilu University of Technology, CHINA*, ²*Tianjin University, CHINA*,
³*University of Sheffield, UK*

- T79-h DESIGN AND STUDY OF A PUMP-FREE MICROFLUIDIC DEVICE FOR SINGLE-CELL ELECTRO-ROTATION DRIVEN BY ELECTRO-OSMOTIC FLOW**
 Jianming Shu, Xijiang Wang, Yue Wang, Jingui Qian, Liang Huang
Hefei University of Technology, CHINA

- W76-h RAPID AMPLIFICATION OF SINGLE-STRANDED DNA BY ON-BEAD PLASMONIC PCR IN AN AUTOMATED MICROFLUIDIC SYSTEM**
 Anni Hu, Yang Bu, Yuze Liu, Yung Ching Lee, Levent Yobas
Hong Kong University of Science and Technology (HKUST), HONG KONG

h - Micro- & Nanofluidics

Manufacturing for Micro- and Nanofluidics

- M76-h EFFICIENT FABRICATION OF SINGLE-UNIT HYBRID PAPER/PDMS MICROFLUIDICS WITH CONTROLLABLE BONDING STRENGTH FOR OIL/WATER SEPARATION AND GRADIENT GENERATOR**
 Phong Vi Lam, Pin-Chuan Chen
National Taiwan University of Science and Technology, TAIWAN

- T80-h INTEGRATED NANOPORE DEVICE FOR ELECTRONIC SINGLE MOLECULE TRAPPING IN FEMTOLITRE CAVITIES FABRICATED BY SELF-ALIGNED ETCHING**
 Xinxin Liu¹, Valentin Dubois¹, Shyamprasad N. Raja¹, Shaufei Cheng²,
 Yuming Yeh², Yingzong Juang², Hanting Hsueh², Weileun Fang³,
 Göran Stemme¹, Frank Niklaus¹
¹*KTH Royal Institute of Technology, SWEDEN*, ²*Taiwan Semiconductor Research Institute, TAIWAN*, ³*National Tsing Hua University, TAIWAN*

h - Micro- & Nanofluidics

Materials for Micro & Microfluidics

W77-h FABRICATING STRETCHABLE LIQUID METAL CIRCUITS WITH A PHYSICAL SACRIFICIAL LAYER
 Kaushal J. Sumaria, Tingyi Liu
University of Massachusetts, Amherst, USA

h - Micro- & Nanofluidics

Other Micro- and Nanofluidics

M77-h A HIGH-ACCURACY PAIR MATCHING METHOD FOR DROPLET MICROFLUIDICS WITH TWO-STATE MEASUREMENT POINTS
 Akihiro Isozaki¹, Yusuke Nasu^{2,3}, Naohiro Terasaka⁴
¹*Ritsumeikan University, JAPAN*, ²*University of Tokyo, JAPAN*,
³*Academia Sinica, TAIWAN*, ⁴*Institute of Science Tokyo, JAPAN*

T81-h A NANOFORREST-INTEGRATED MICROFLUIDIC COOLING DEVICE FOR HIGH-POWER CHIPS
 Qirui Zhang^{1,2}, Zizhen Wang^{1,2}, Qiming Guo^{1,2,3}, Huabin Yang^{1,2,3},
 Yizhi Shi^{1,2,3}, Na Zhou^{1,2}, Xiaoli Tian^{1,2}, Haiyang Mao^{1,2}
¹*Chinese Academy of Sciences (CAS), CHINA*, ²*University of Chinese Academy of Sciences, CHINA*, ³*Shandong Key Laboratory of Intelligent Sensing Chip and Sysyem, CHINA*

W78-h AN ELECTRO-DEWETTING BASED MICROFLUIDIC PIXEL DEVICE
 Qining Leo Wang, Chang-Jin "CJ" Kim
University of California, Los Angeles, USA



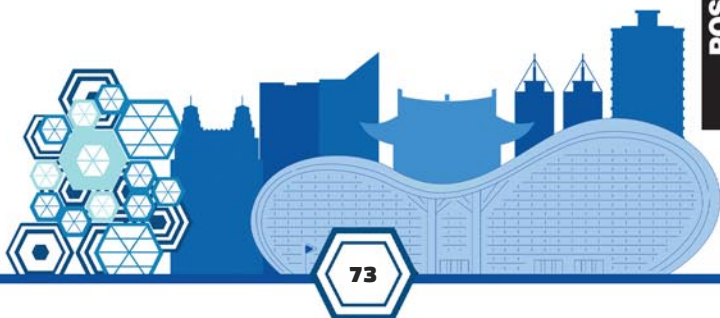
Kaohsiung – Pier 2 Art Zone. Source: Kaohsiung City Government

i - Open Poster

- M78-i SILICON ELECTRON EMITTER INTEGRATED WITH LED FOR X-RAY GENERATOR WITH HIGH EMISSION CURRENT AND LONG LIFETIME**
 Hyo-jin Nam, Eunju Hong, Giwon Lee, Jinah Kim, Youngsik Kim, Byungkee Lee
LG Electronics, KOREA
- W79-i MICROFABRICATION OF BIORESORBABLE ZNO TFTS FOR UV-RESPONSIVE AND SUSTAINABLE ELECTRONICS**
 Deniz Aktas, Levent Beker
Koç University, TURKEY
- M79-i PACKAGE STRUCTURE FOR GAS SENSOR BASED ON THERMAL INFRARED DETECTION**
 Luca Maggi, Marco Del Sarto, Marco Ferrera, Michele Dellutri, Giuseppe Bruno, Silvia Nicoli, Matteo Bironi, Anita Previdi
STMicroelectronics, ITALY
- W80-i SILENT SPEECH INTERFACE ON THE HAND USING LIQUID METAL AND SOFT MATERIALS**
 Yuta Kurotaki^{1,2}, Reitaro Yoshida², Shusuke Yamakoshi¹, Yutaka Isoda¹, Tamami Takano¹, Yuji Isano¹, Yusuke Miyake², Kentaro Kuribayashi², Hiroki Ota¹
¹Yokohama National University, JAPAN, ²GMO Pepabo, Inc., JAPAN
- M80-i GAP VARIATION ESTIMATION IN MEMS GYROSCOPE SUBJECTED TO MECHANICAL STRESS**
 Davide Bernabucci, Patrick Fedeli, Gianfranco Javier Yallico Sanchez, Luca Guerinoni, Luca Falorni
STMicroelectronics, ITALY
- W81-i A ROBUST PIEZORESISTIVE PRESSURE SENSOR**
 Hung-Lin Yin, Yen-Liang Lin, Wu-Hsing Yi
Asia Pacific Microsystems, Inc, TAIWAN
- M81-i WORLD'S SMALLEST COMMERCIALIZED PARTICULATE MATTER SENSOR ENABLED BY AN INNOVATIVE SEMICONDUCTOR PACKAGE DESIGN**
 Tobias Henn¹, Steve Lin¹, Nico Chou¹, Wallace Chuang¹, Chin Yi Cho¹, Anna Kamolawat², Martin Edel², Joachim Friedl², Florian Grabmaier³, Robert Weiss³
¹Robert Bosch Ltd., TAIWAN, ²Robert Bosch GmbH, GERMANY, ³Bosch Sensortec GmbH, GERMANY
- T82-i IMPEDANCE SENSING OF MIGRATING CELLS IN MICROCHANNEL WITH TOPOGRAPHY GUIDANCE**
 Xiao Hong, Stella W. Pang
City University of Hong Kong, HONG KONG

i - Open Poster

- M82-i** **NUMERICAL FLUID-STRUCTURE INTERACTION WORKFLOW FOR PATTERN COLLAPSE PREDICTION DURING SEMICONDUCTOR FABRICATION**
 Ashraful Islam, Gabriel Pichon, Rafael Salazar-Tio, Ganapathi Balasubramanian, Bernd Crouse, Junghan Kim, Seokwon Hwang, Yeongchan Yu
Dassault Systemes Simulia, USA
- W82-i** **LEAD-FREE PIEZOELECTRIC MEMS ACOUSTIC EMISSION SENSOR COMPATIBLE WITH COMMERCIAL BULK AE SENSORS**
 Yongfang Li, Yuki Ueda, Takashi Usui, Kazuo Watabe
Toshiba Corporation, JAPAN
- M83-i** **ADVANCING MICROFLUIDIC ENCAPSULATION TECHNIQUES USING SURFACE ACOUSTIC WAVES AND MICROVALVES**
 Mohammad Reza Raveshi, Ali Vafaie, Sagar N. Agnihotri, Rajneesh Bhardwaj and Adrian Neild
Monash University, AUSTRALIA
- T83-i** **MACHINE LEARNING TO ENABLE GAS CLASSIFICATION FOR MEMS GAS SENSING PLATFORM**
 Changting Xu¹, Jiezhong Yang^{1,2}, Philip Papageorgiou¹, Kostadin Djordjević¹, Jim Cheng¹
¹Qualcomm Technologies Inc, USA, ²Harvard University, USA
- W83-i** **OPTIMIZATION OF THIN-FILM MAGNETOELECTRIC CANTILEVER THROUGH DUAL MODULATION OF MAGNETIC AND ELECTRIC BIAS FIELDS**
 Yuxi Wang^{1,2,3,4}, Lihui Jin¹, Mingye Du¹, Jiawei Li¹, Daozheng Luo¹, Ruihong Xiong¹, Tao Wu^{1,2}
¹ShanghaiTech University, CHINA, ²University of Chinese Academy of Sciences, CHINA
- M84-i** **CRACK PRESERVING EFFECT INDUCED BY E-BEAM IRRADIATION IN ULTRATHIN METAL FILMS ON ELASTOMER MEMBRANES FOR FLEXIBLE SENSORS***
 Benjamin Sittkus¹, Julien Petit¹, Gerald Urban¹, Ulrich Mescheder^{1,2}
¹Furtwangen University, GERMANY, ²University of Freiburg, GERMANY
- T84-i** **SELF-ASSEMBLED MICRO-NANO STRUCTURES MANUFACTURING STRATEGY BASED ON CMOS-COMPATIBLE SU8 PHOTORESIST**
 Zhi-Qi Dong, Kai-Ming Hu, Rui-Jia Xiang, Tian-Yu Zhao, Jun-Feng Zhou, Guang Meng, Wen-Ming Zhang
Shanghai Jiao Tong University, CHINA



i - Open Poster

- W84-i** **PIEZOELECTRICALLY DRIVEN INCH WORM MOTOR FOR LARGE FORCE AND STROKE APPLICATIONS IN IMPLANTS**
Ulrich Mescheder^{1,2}, Bahman Azarhoushang^{1,2}, Volker Bucher¹
Jahangir Khosravi¹, Sonja Müller^{1,2},
¹Furtwangen University, GERMANY, ²University of Freiburg, GERMANY
- M85-i** **MEMS AS ULTRAFAST OPTICS FOR MANIPULATING X-RAY PULSES WITH PICOSECOND RESOLUTION**
Jin Wang, Pice Chen, Donald. A. Walko, Il-Woong Jung,
Daniel Lopez, and Gopal K. Shenoy
Argonne National Laboratory, USA
- T85-i** **LASER DOPPLER VELOCIMETER USING ON-CHIP MICRO FRINGE PATTERN PROJECTOR FOR MICROFLUIDICS**
Hiroki Kumon, Masatoshi Takahashi, Kazuyoshi Hirose,
Shu Honma, Hiroki Kamei, Tomohiko Hirano,
Masakazu Katsumata, Hidenao Yamada
Hamamatsu Photonics K.K., JAPAN
- W85-i** **TUNABLE MEMS OSCILLATOR WITH LARGE FREQUENCY TUNING RANGE VIA NONLINEARITY**
Yu-Chi Chuang, Yuan-Chieh Lee, Zong-Xian Guan,
Hsiang-Chun Hsiao, Yi Chiu
National Yang Ming Chiao Tung University, TAIWAN
- M86-i** **OPTIMIZATION AND INVESTIGATION OF MINIATURIZED ELECTROSTATIC MEMS ACTUATOR TO ENABLE TUNABILITY IN GRAPHENE BASED LIGHT SOURCES**
Karman Selvam¹, Nooshin Saeidi^{1,2}, Maik Wiemer¹, Harald Kuhn^{1,2},
Anna Kozłowska³, Kamila Leśniewska-Matys³, Rafał Stankiewicz³,
Martin Kalbáč⁴, Maryam Ehsani⁵, Yvonne Joseph⁵
¹Fraunhofer Institute ENAS, GERMANY, ²Chemnitz University of Technology, GERMANY, ³Institute of Microelectronics and Photonics, POLAND, ⁴J. Heyrovsky Institute of Physical Chemistry, CZECH REPUBLIC, ⁵TU Bergakademie Freiberg, GERMANY
- T86-i** **SINGLE-TRANSDUCER ULTRASONIC AIRFLOW-METER**
Stefano Sanvito¹, Marco Passoni², Marco Ferrera²
¹University of Bergamo, ITALY, ²STMicroelectronics, ITALY
- W86-i** **PREPARING FOR NewATHENA FLIGHT PRODUCTION: RECENT DEVELOPMENTS IN UPSCALING SPO PLATE MANUFACTURING TECHNOLOGY**
Jeroen Haneveld¹, Bart Schurink¹, Marko Blom¹, Mathijs Bosman¹,
Bastiaan van Dam¹, Arenda Koelewijn¹, Jan-Joost Lankwarden¹,
Mark Olde Riekerink¹, Ronald Start¹, Maurice Wijnperle¹,
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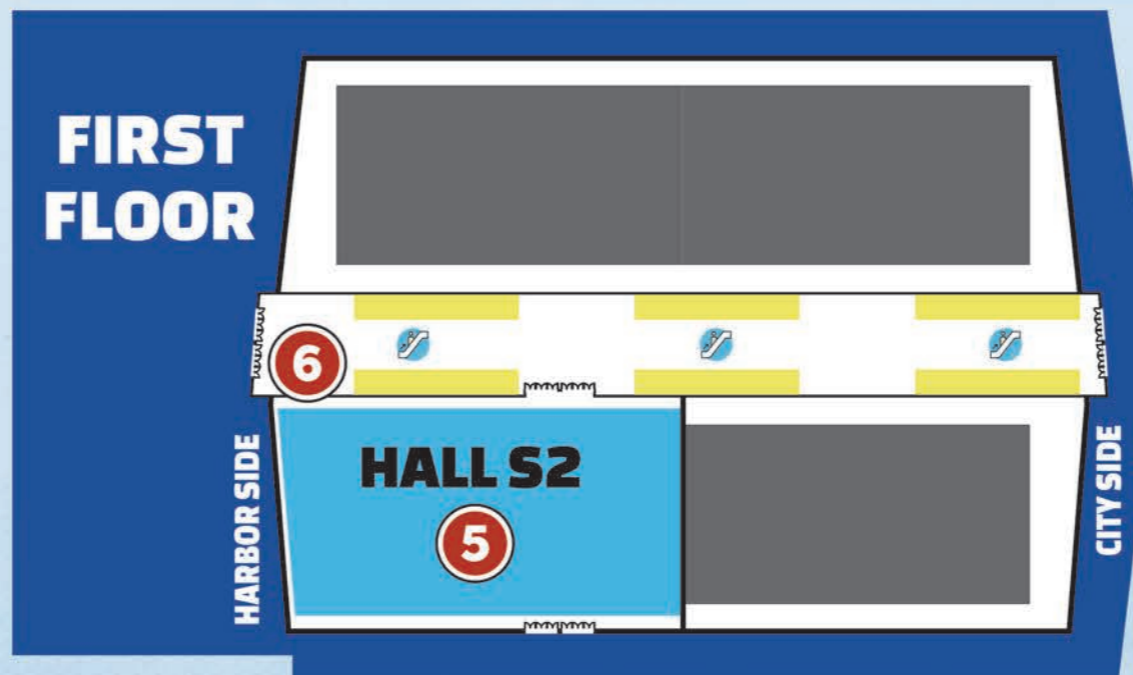


FOLD OUT FOR POSTER PRESENTATION FLOOR PLAN(S)

MONDAY 15:10 – 17:00	TUESDAY 13:00 – 15:00	WEDNESDAY 15:10 – 17:10
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CLASSIFICATION (last character of poster number)

a - Bio and Medical MEMS
b - Emerging Technologies and New Opportunities for MEMS/NEMS
c - Industry MEMS and Advancing MEMS for Products and Sustainability
d - MEMS & NEMS Materials, Fabrication and Packaging
e - MEMS Actuators and PowerMEMS
f - MEMS Physical and Chemical Sensors
g - MEMS/NEMS for Optical, RF and Electromagnetics
h - Micro- & Nanofluidics
i - Open Posters



THIRD FLOOR

- 1** Room 301
 - Plenary Presentations I-III
 - Welcome Address & Announcements
- 2** Room 304a
 - Plenary Presentation IV
 - Concurrent Session A
 - Awards Ceremony
 - Industry Sessions
- 3** Room 304b
 - Concurrent Session B
- 4** Room 305
 - Welcome Reception

FIRST FLOOR

- 5** Hall - S2
 - Exhibits
 - Poster Sessions
 - Breaks & Lunches
- 6** Central Boulevard - West Lobby
 - Student Mixer
 - Women in Engineering Luncheon

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